

Two-dimensional materials and applications

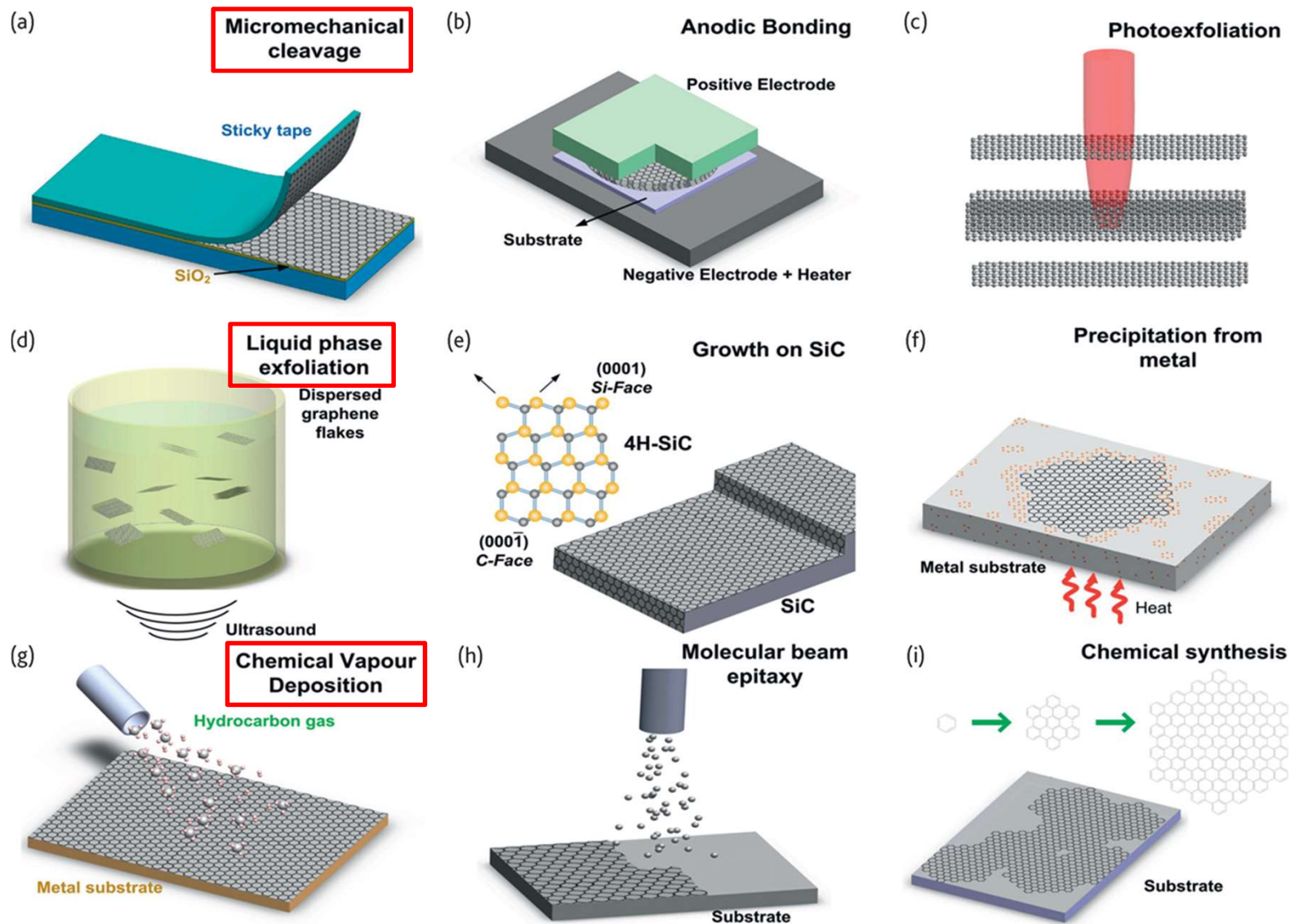
5. Production of 2D Materials

Part 1

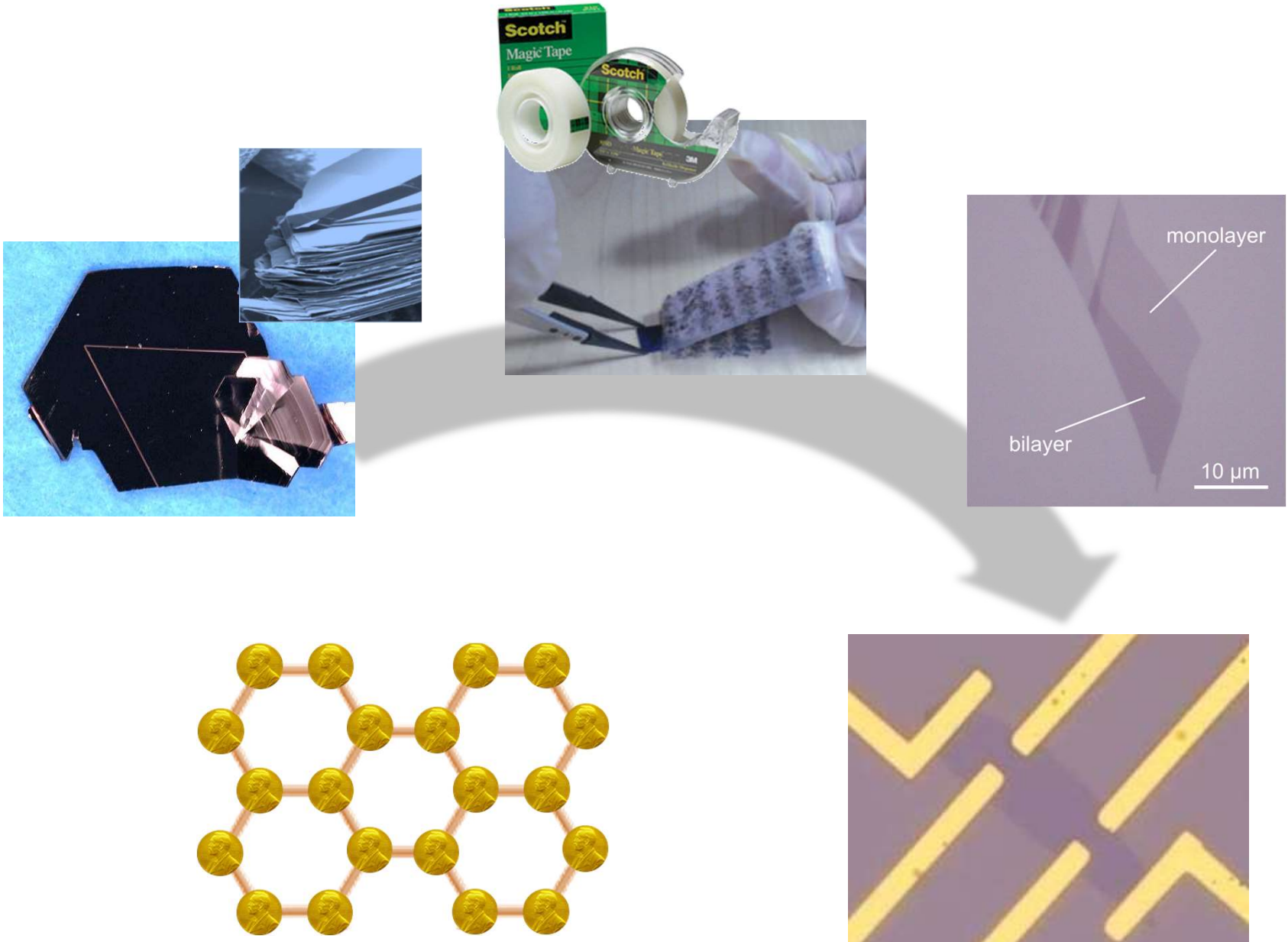


서울대학교
SEOUL NATIONAL UNIVERSITY

How to Make 2D Materials

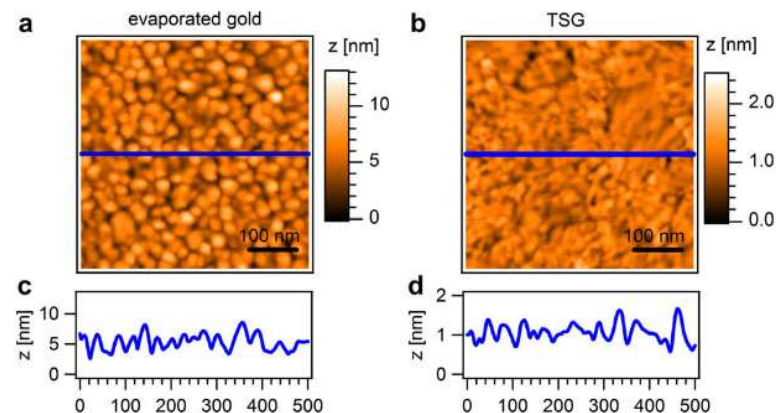
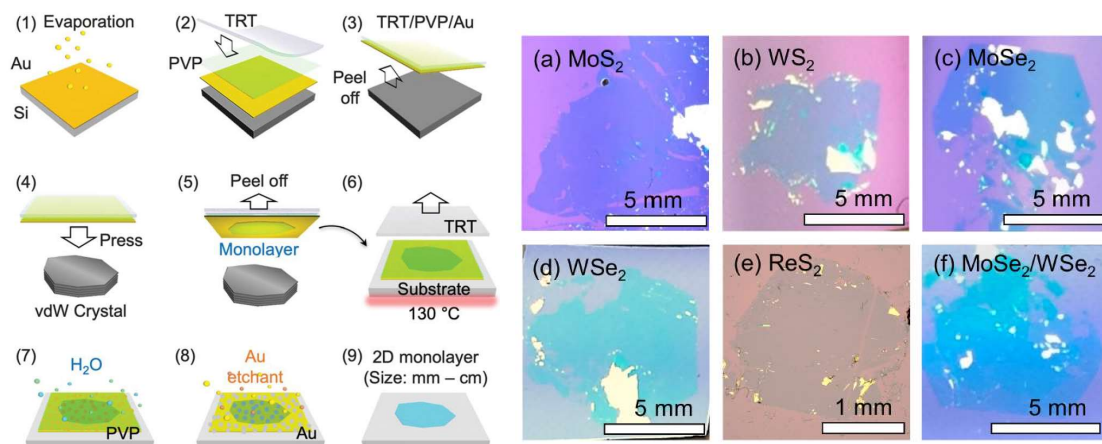


Mechanical Exfoliation (Scotch Tape Method)



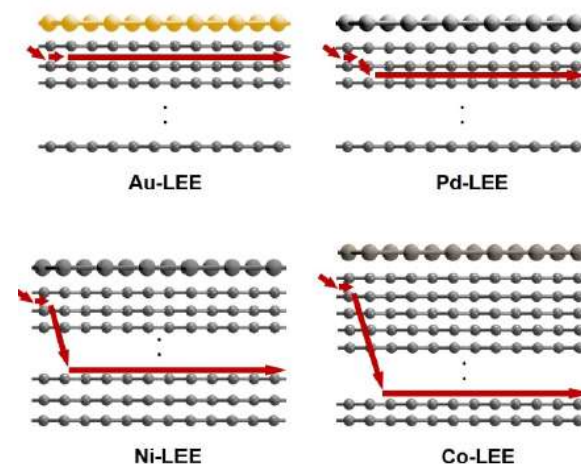
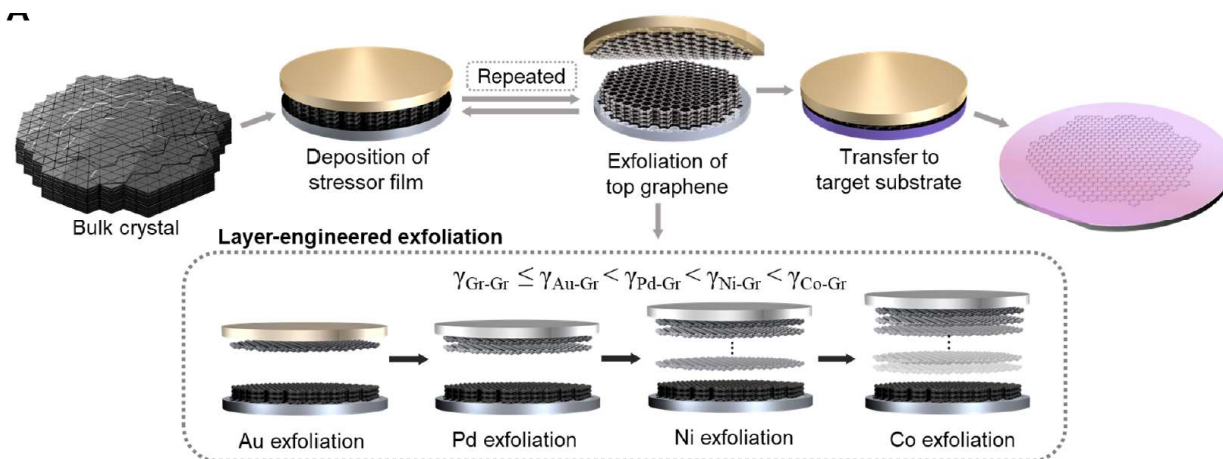
Advanced Mechanical Exfoliation

Mechanical exfoliation by using flat Au film



A. Rueda et al. Surface Science (2009)

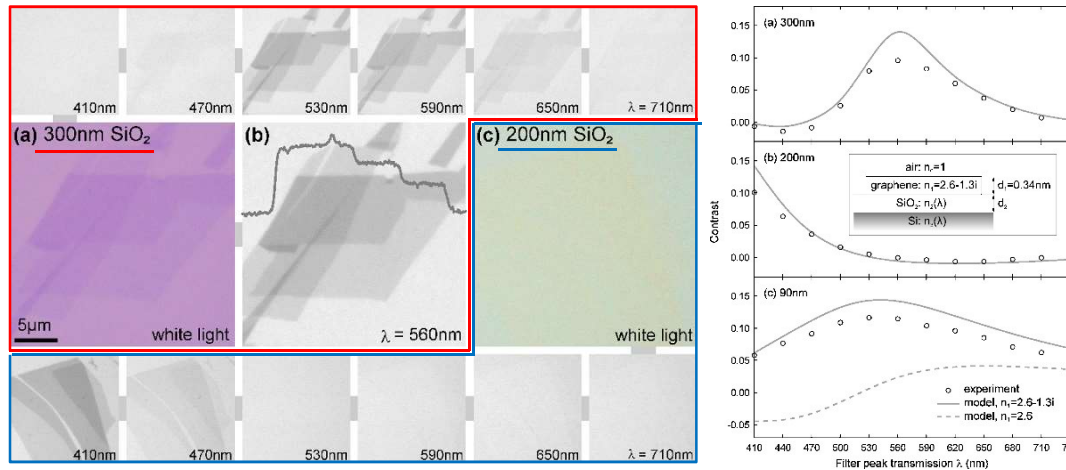
Layer-engineered exfoliation by using deposited metal films



Moon et al., Sci. Adv. (2020)

Optical Contrast of Graphene

Graphene's visibility depending on substrate and light wavelength

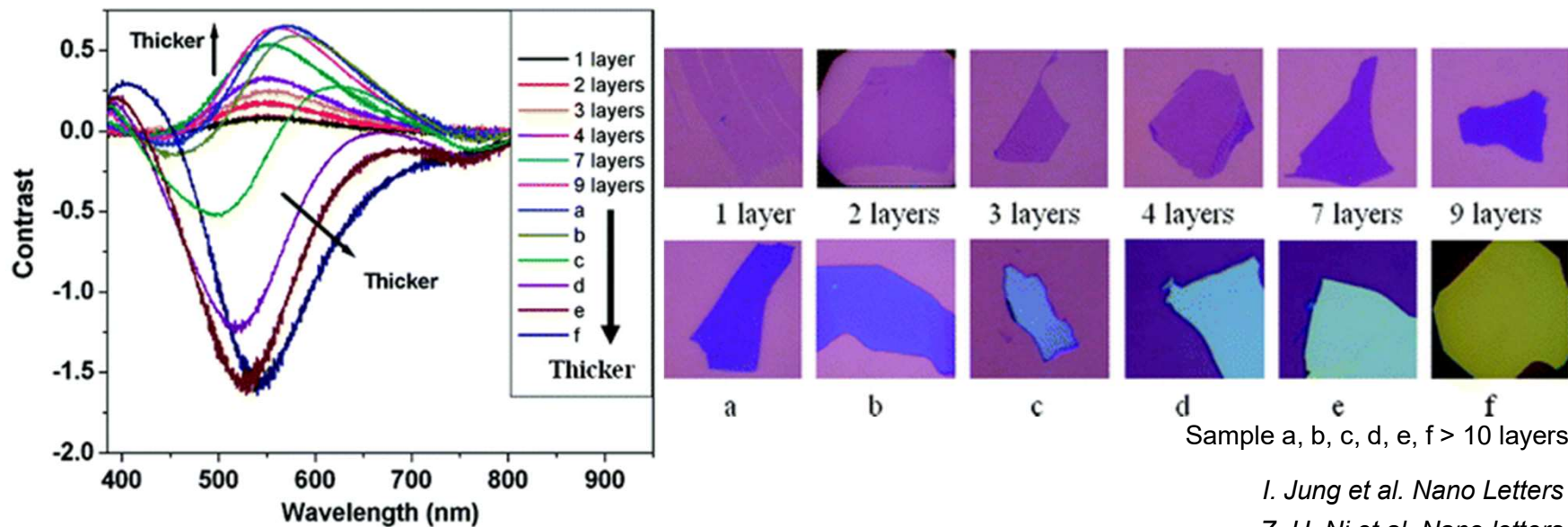


$$Contrast(\lambda) = \frac{R_0(\lambda) - R(\lambda)}{R_0(\lambda)}$$

where, $R_0(\lambda)$ is the reflection spectrum from the SiO_2/Si substrate and $R(\lambda)$ is the reflection spectrum from graphene sheet.

P. Blake et al. Applied Physics Letters (2007)

Optical contrast depending on number of layers

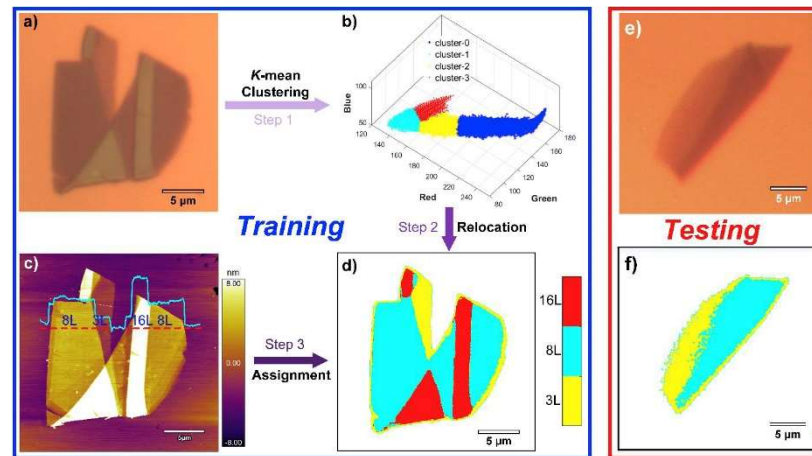


I. Jung et al. Nano Letters (2007)

Z. H. Ni et al. Nano letters (2007)

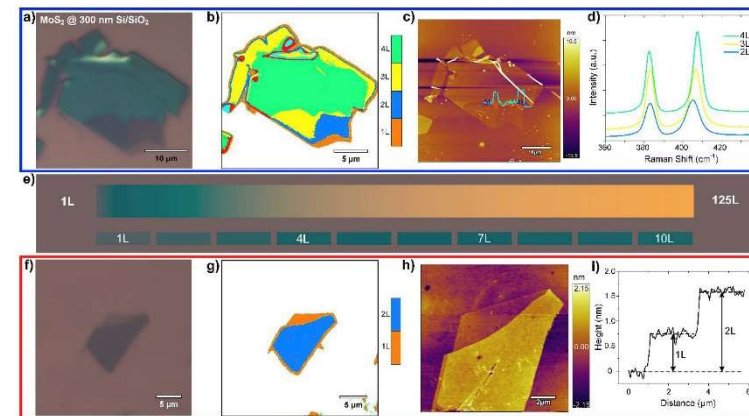
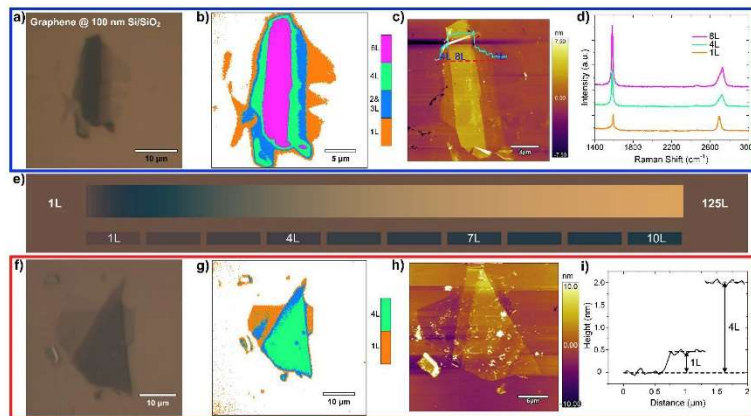
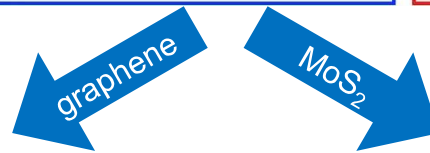
Identification of Number of Layer Number

machine learning



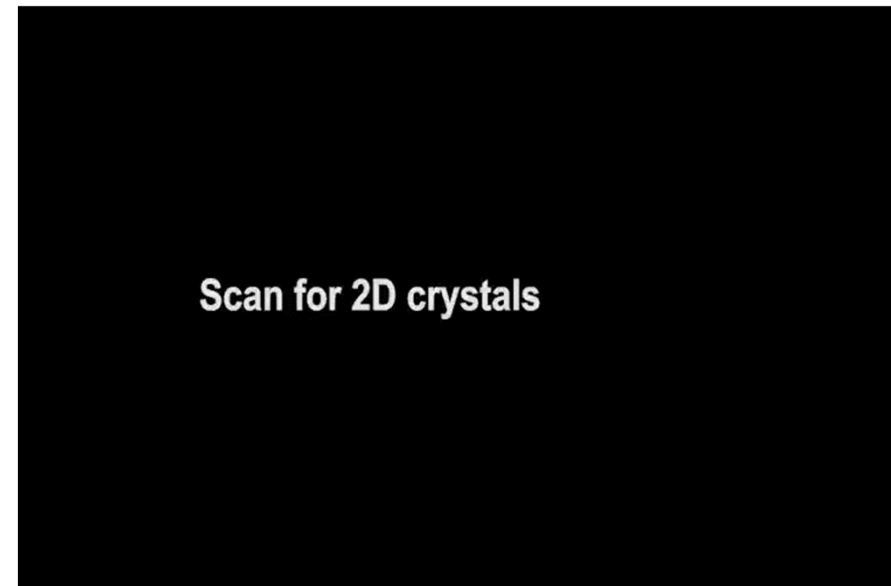
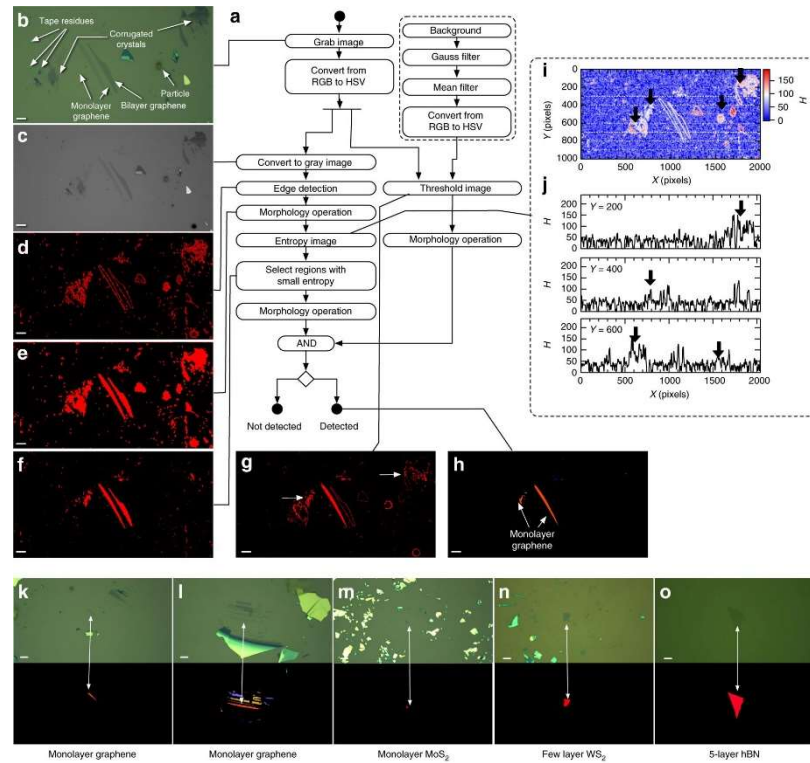
Three effective indexes

- optical contrast
- total color difference
- red-green-blue

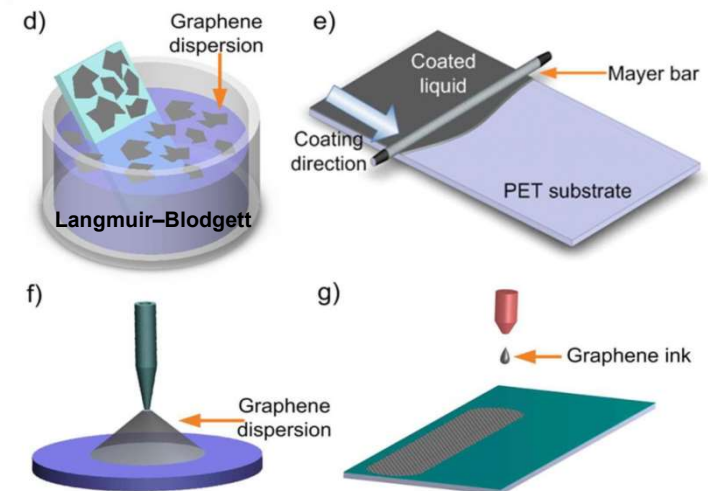
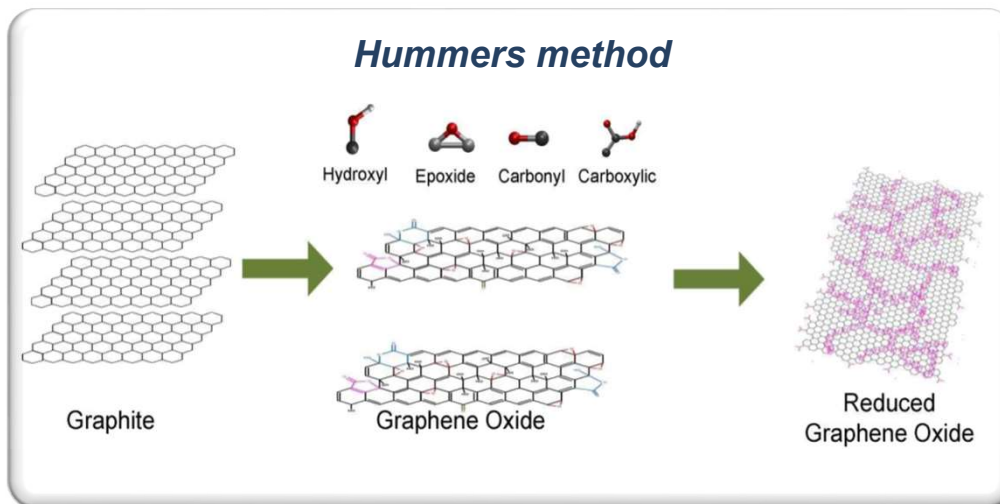
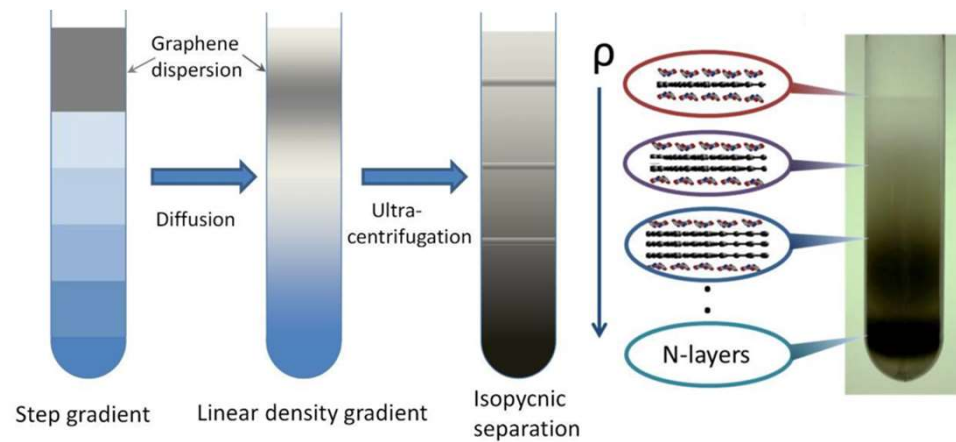


Auto-finding Flakes of 2D Materials

Auto-finding flakes of 2D materials



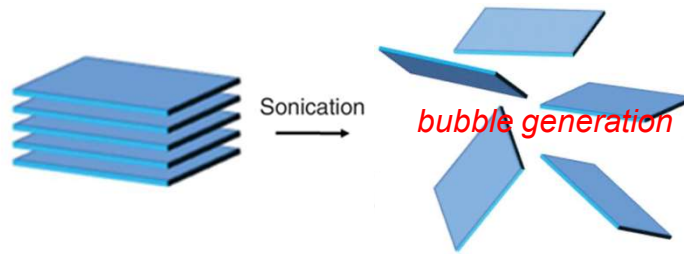
Liquid Exfoliation



F. Bonaccorso et al. Materials Today (2012)
K. R. Paton et al. Nature Materials (2014)
A. C. Ferrari et al. Nanoscale (2014)

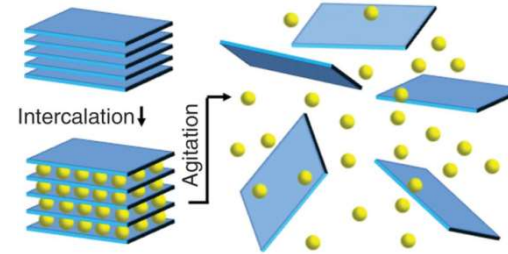
Liquid Exfoliation

Ultrasonication method



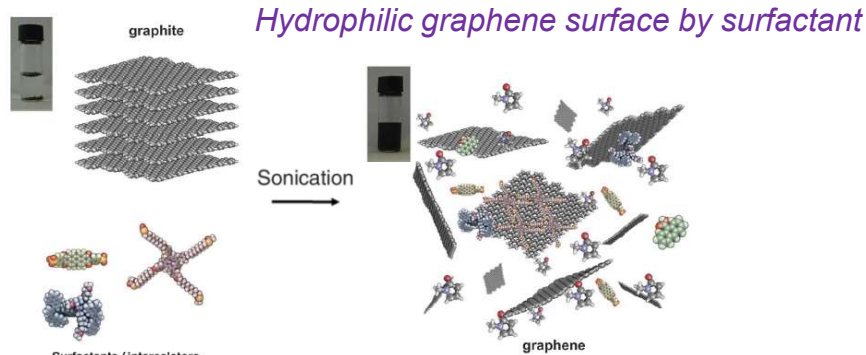
V. Nicolosi et al. Science (2013)

Hummers method



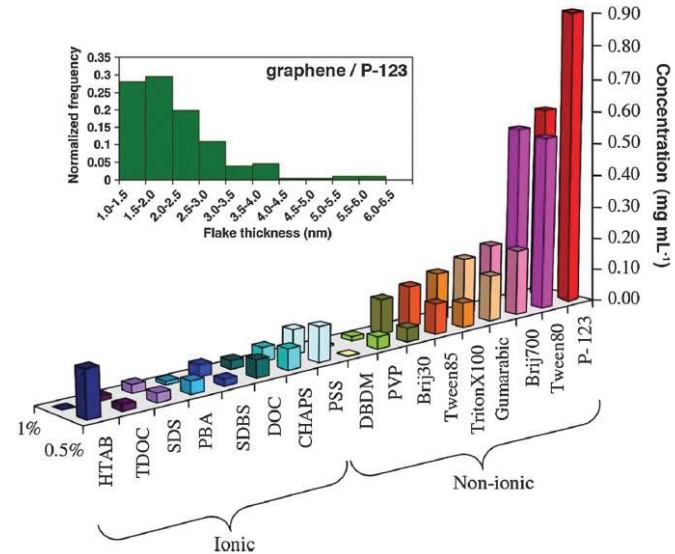
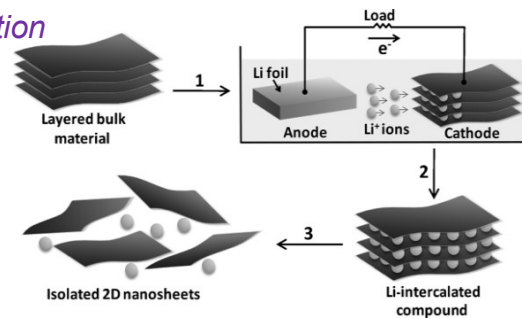
Graphene oxidation (H_2SO_4 or $KMnO_4$) → Formation of hydroxyl or epoxide groups → Water Intercalation by hydrophilicity → Ultrasonication → Reduction

Intercalation method

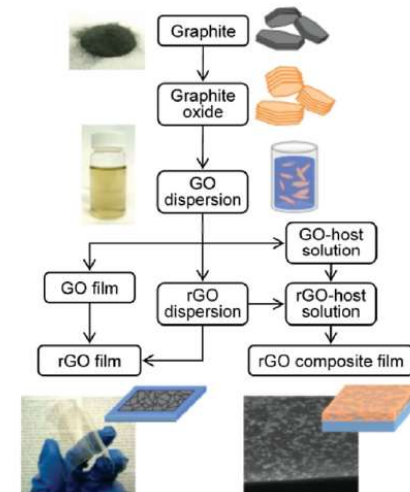
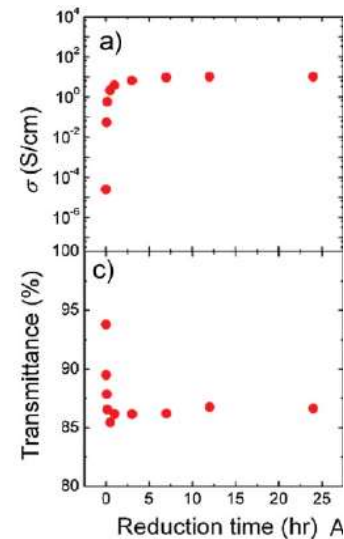
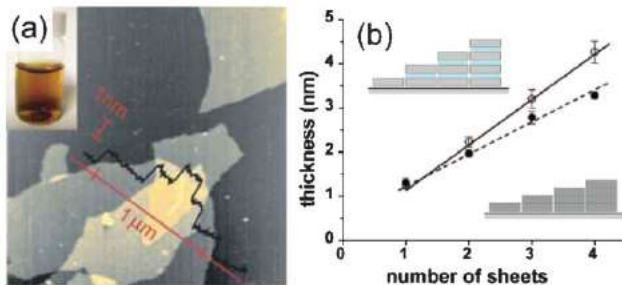
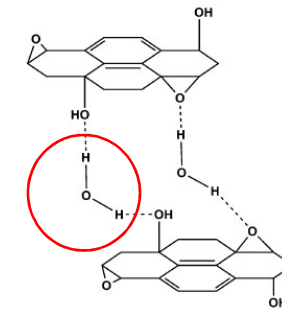
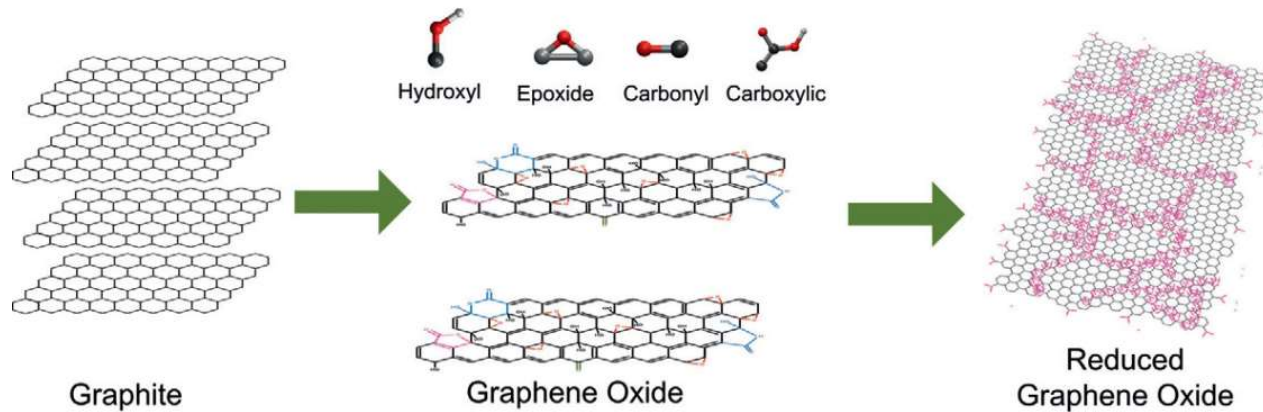


A. Ciesielski et al. Chem. Soc. Rev. (2014)

Li intercalation



Oxidation/Reduction for rGO

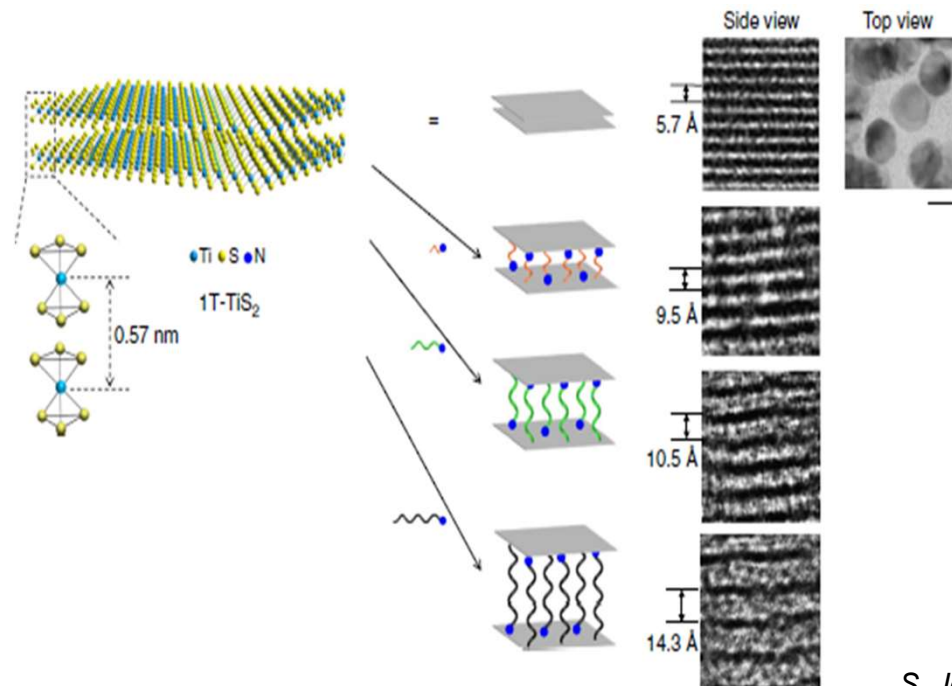
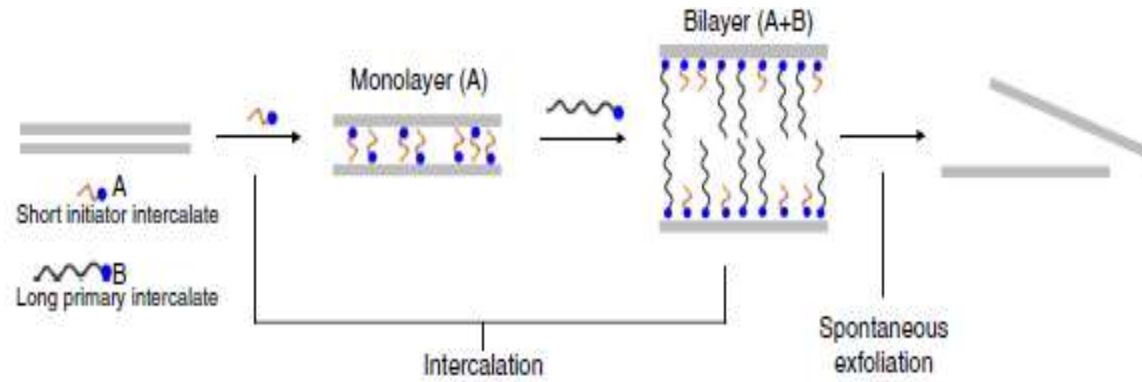


Oxidation / Reduction

Mechanism	Attachment/detachment of functional groups including oxygen
Properties	Control of property by varying types/amounts of oxide Scattering of electrons due to chemical groups/defects

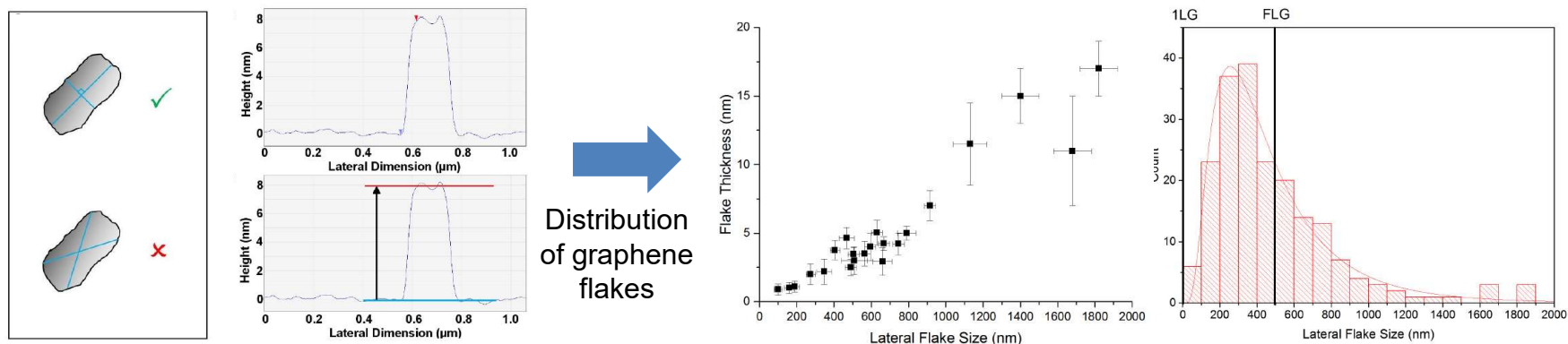
Advanced Liquid Exfoliation

Tandem molecular intercalation



Standard Category of Graphene

Determination of thickness and size of graphene flakes



Graphene; graphene layer; single layer graphene; monolayer graphene

Single layer of carbon atoms with each atom bound to three neighbors in a honeycomb structure

Bilayer graphene (2LG)

Two-dimensional material consisting of two well-defined stacked graphene layers

Few-layer graphene (FLG)

Two-dimensional material consisting of three to ten well-defined stacked graphene layers

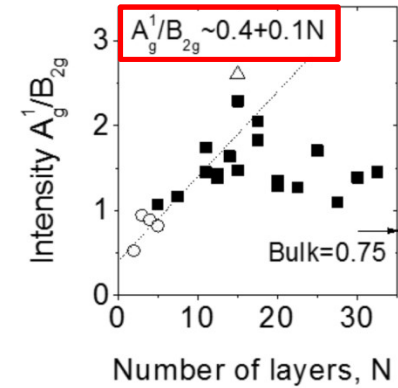
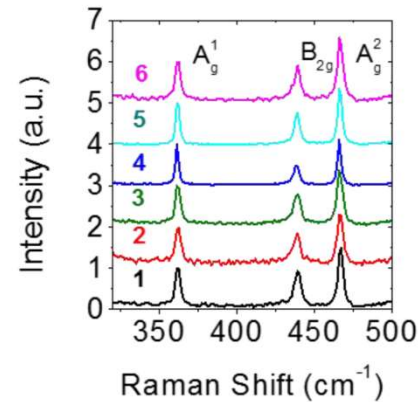
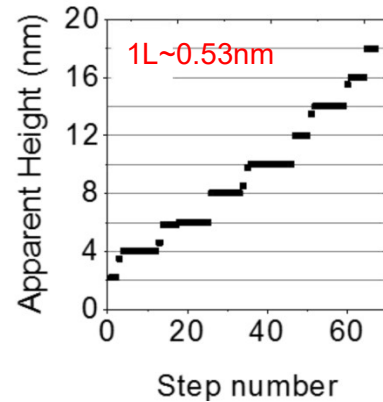
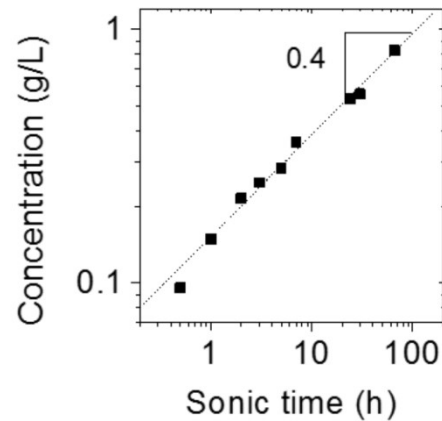
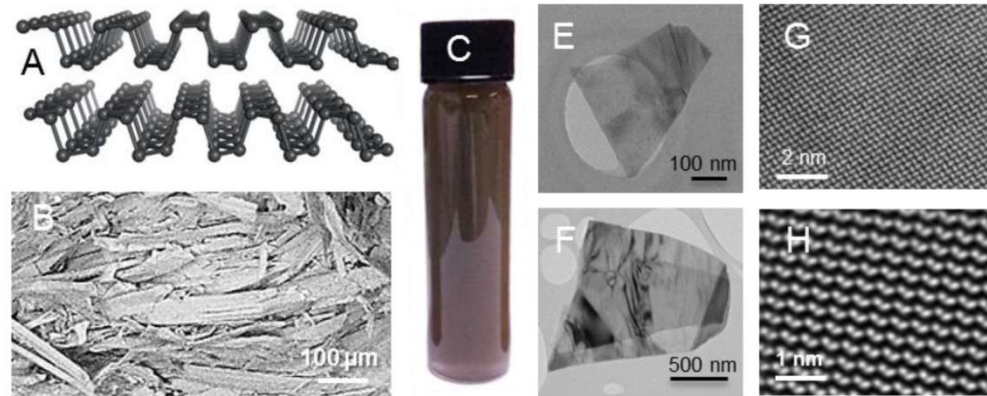
Graphene nanoplatelet (GNP)

Thickness between 1 and 3 nm and lateral dimensions ranging from ≈ 100 nm to $100 \mu\text{m}$.

Thickness of graphene monolayer is 0.34 nm. But, it is not correspond to single layer graphene on substrate because interaction between substrate and graphene is different from that between graphene layers. So, we have to confirm the number of layers of graphene on substrate using Raman spectroscopy and AFM. For example, even though the thickness of a graphene flake is measured as 1.0 nm with AFM, it might be a single layer graphene as confirmed by Raman spectroscopy. Nevertheless, subsequent layers have a corresponding 0.34 nm step height (*i.e.* 2LG is ~ 1.34 nm and 3LG is ~ 1.68 nm-thick).

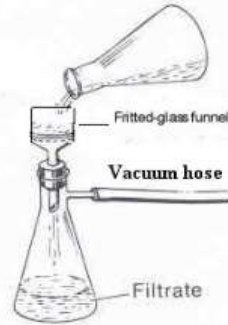
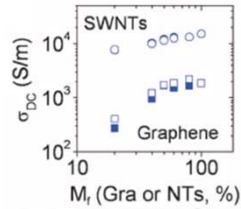
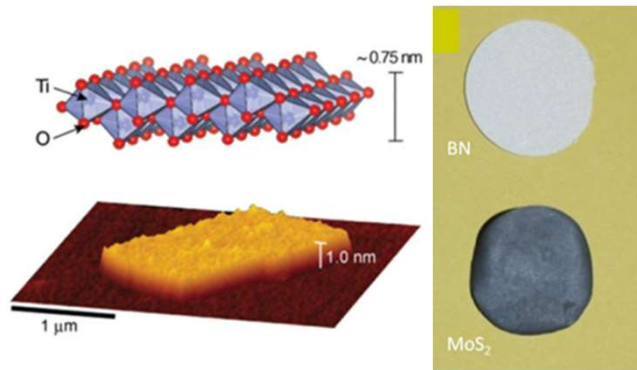
Liquid Exfoliation of Black Phosphorous

Sonication in *N*-cyclohexyl-2-pyrrolidone (CHP)

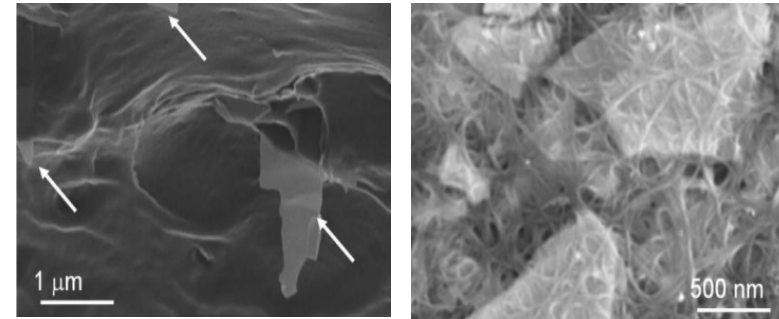


Applications of Liquid-Exfoliated 2D sheets

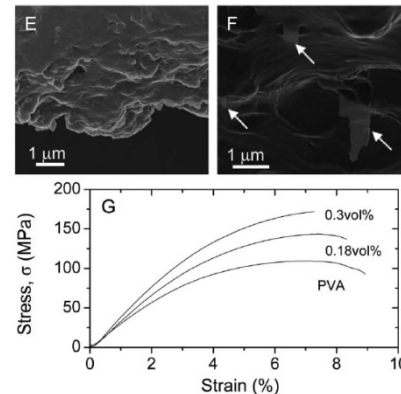
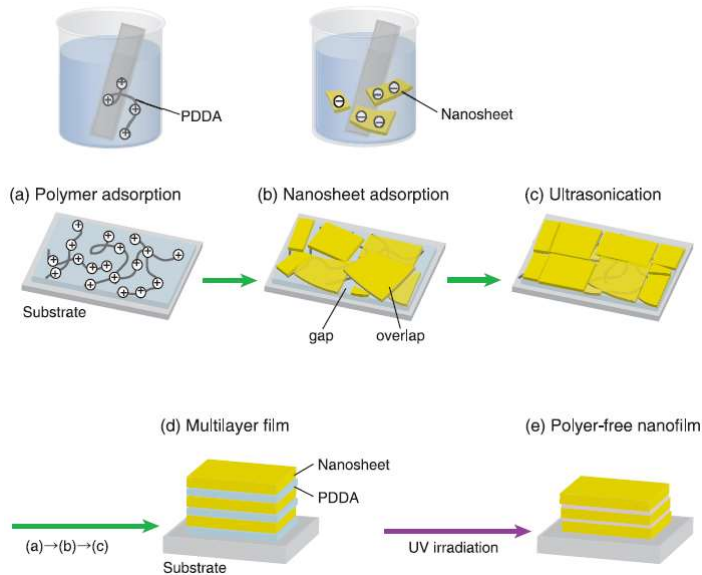
Formation of thin or free-standing films



Mixing with other materials (polymer composites)

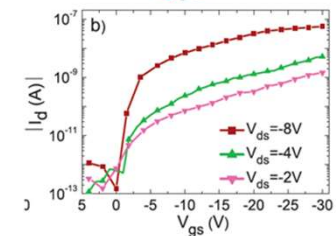
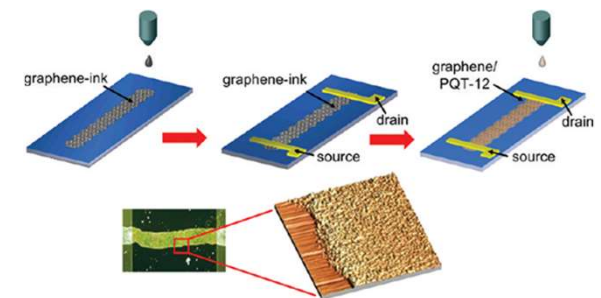


Formation of 2D oxide films

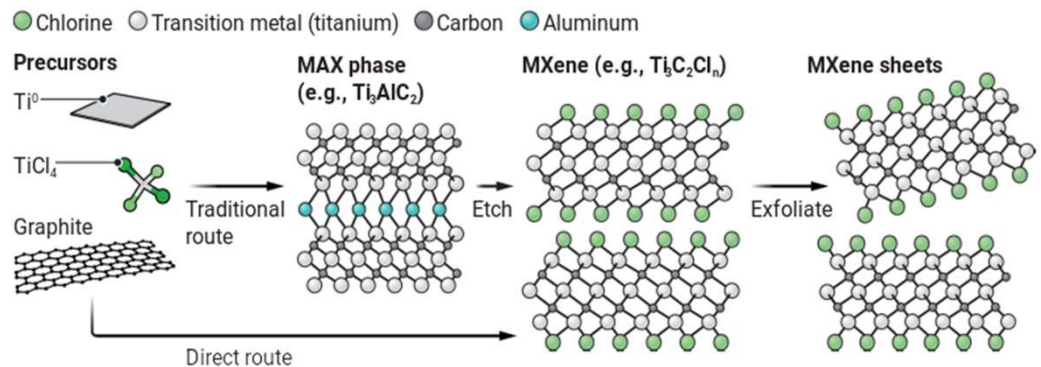


	<u>Ti_{0.87}O₂ nanosheet</u>	TiO ₂ (rutile)	TiO ₂ (anatase)
Dielectric constant (exp.)	125	80-100	30-40
Electronic permittivity (calc.)	9.81	8.22	6.05

Printing of 2D materials



Direct route to synthesize Mxene

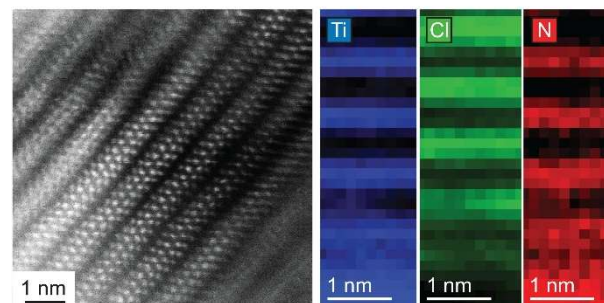
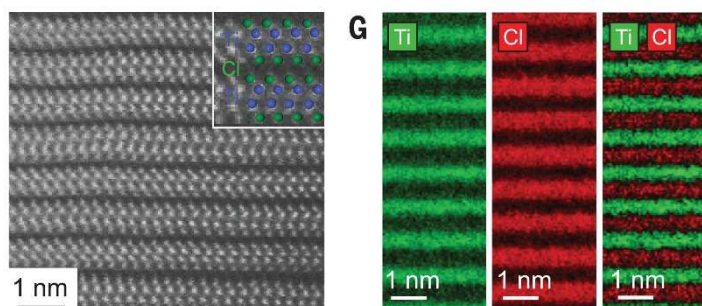
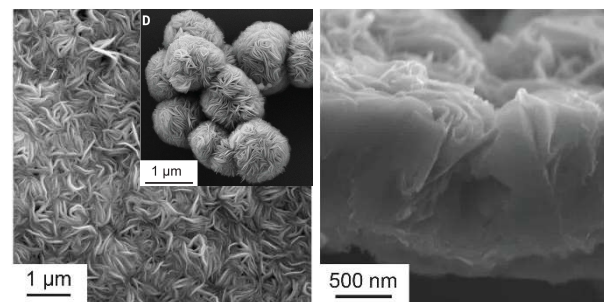
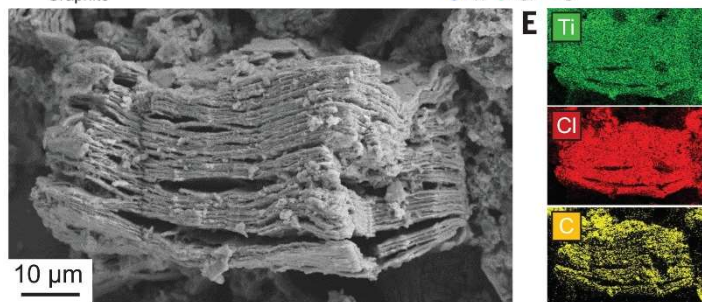
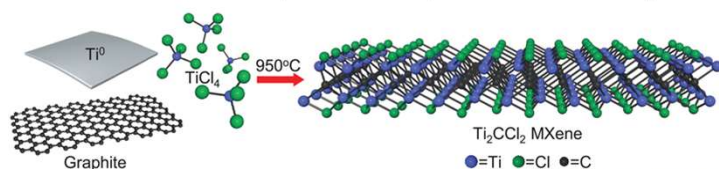


Precursors of the desired elements are heated together to produce a MAX phase.

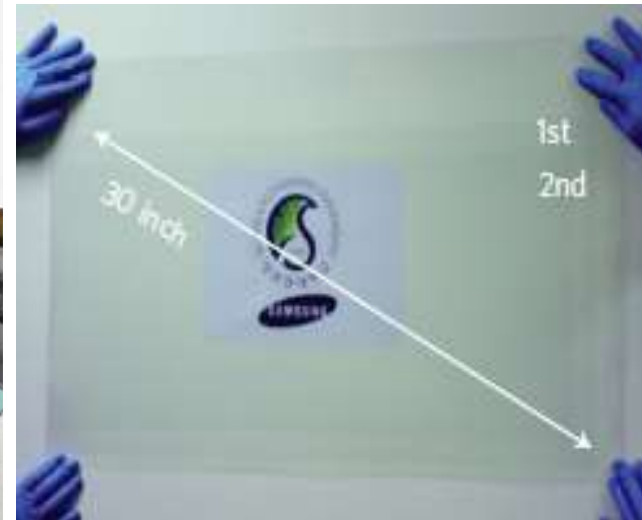
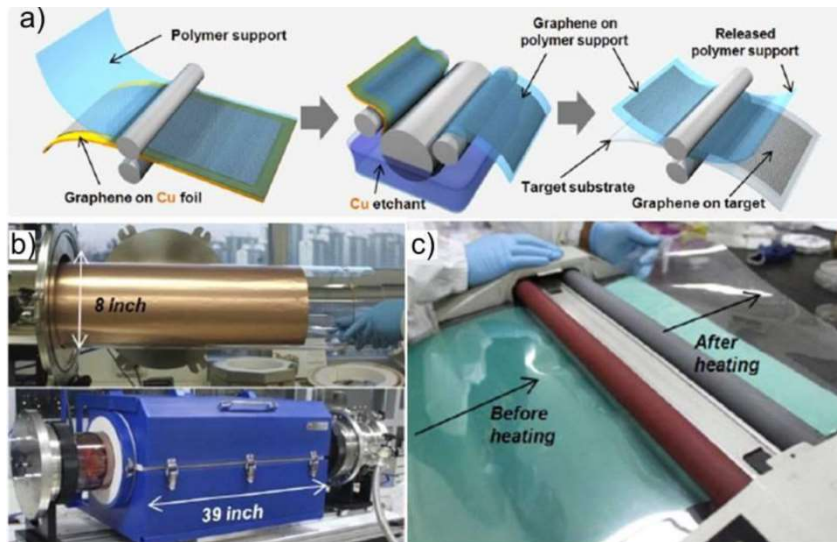
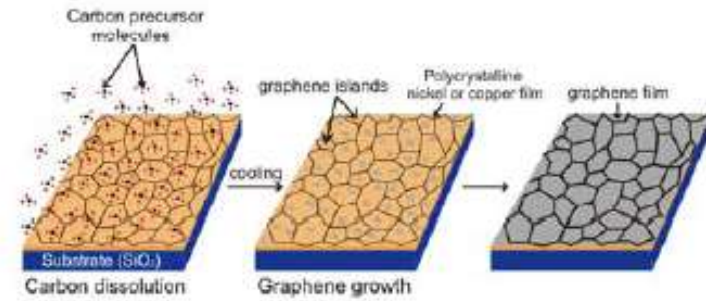
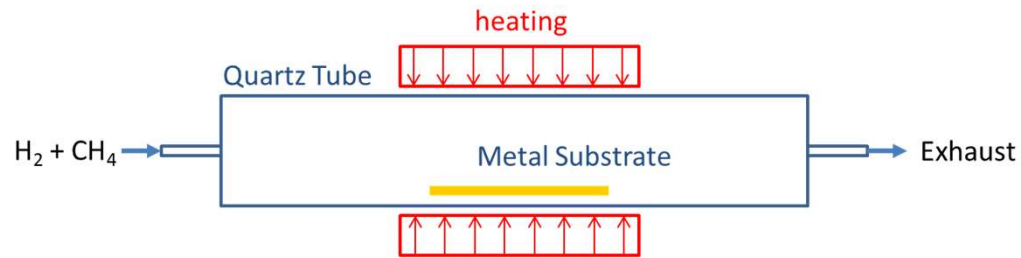
Once synthesized, the MAX phase is treated with hydrofluoric acid or another etchant to remove A atoms and produce a layered MXene phase.

The bulk MXene material can then be exfoliated into individual sheets for applications.

Science 379, 1189-1190 (2023)



Chemical Vapor Deposition (CVD)

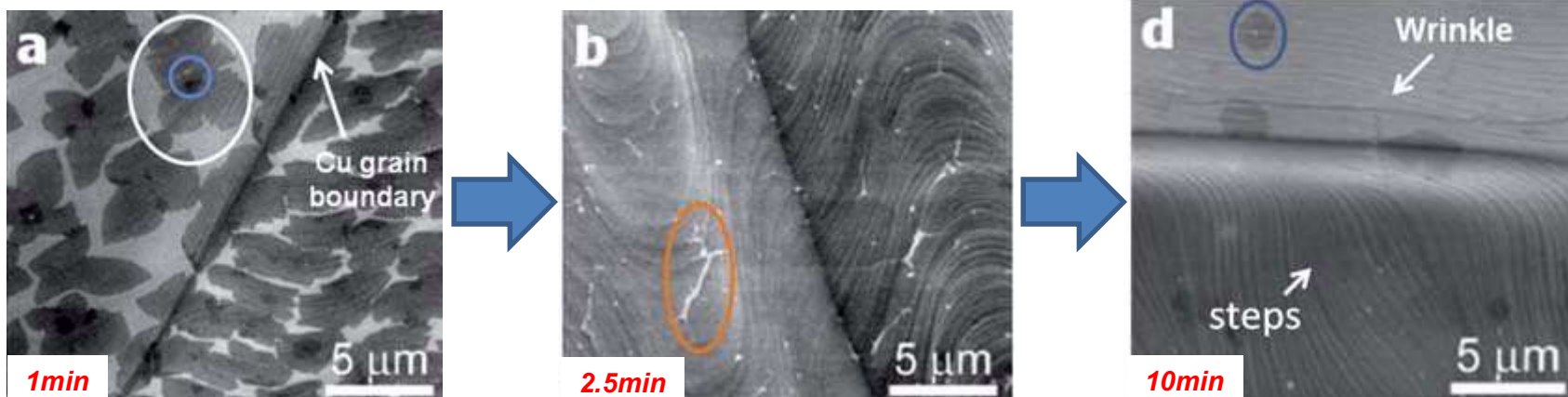


X. Li et al. Science (2009)
 S. Bae et al. Nature Nanotech. (2010)
 D. Jariwala et J Nanosci Nanotechnol.. (2011)

Chemical Vapor Deposition (CVD)

Factors to Influence Characteristics of Graphene

- *Nucleation : density of grains, homogeneity*
 - Pre-treatment condition*
 - Partial pressure of methane and total growth pressure*
 - Nucleation sites – atomically thin terraces, defects, protrusions, evaporated copper during process*
- *Growth : grain size, shape*
 - Partial pressure of hydrogen and methane and total pressure*
 - Growth time*
- *Metal substrate : Cu, Ni, Au, Pt, Fe ...*
 - Catalytic effect (e.g. Cu)*
 - Precipitation and surface segregation (e.g. Ni)*
 - Roughness, crystal orientation*




Chemical Vapor Deposition (CVD)



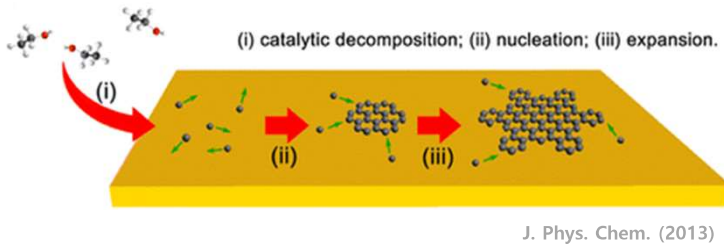

S2.mov




S3.mov

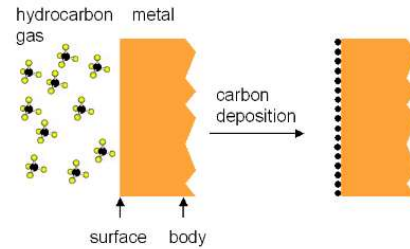
Effect of Growth Templates in CVD

Growth of graphene on Cu

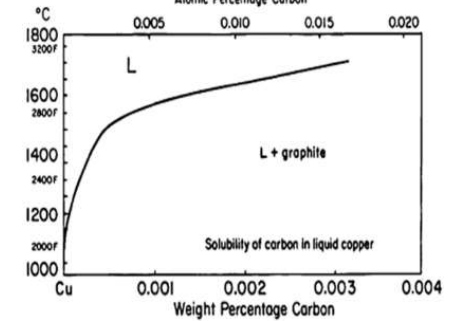


- Cu is an efficient catalyst for decomposing hydrocarbon gas.
- Extremely low carbon solubility
- No formation of copper carbides.

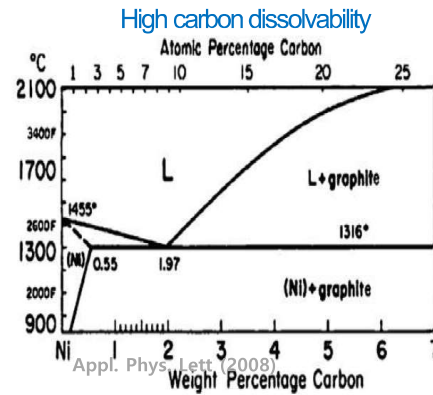
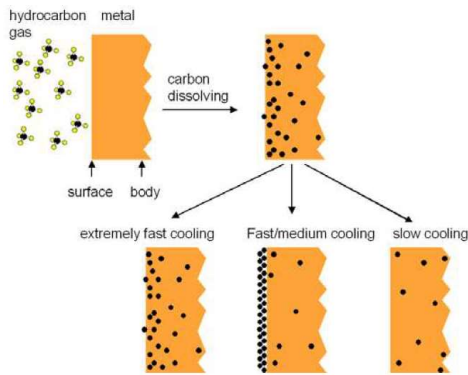
Self-limiting process



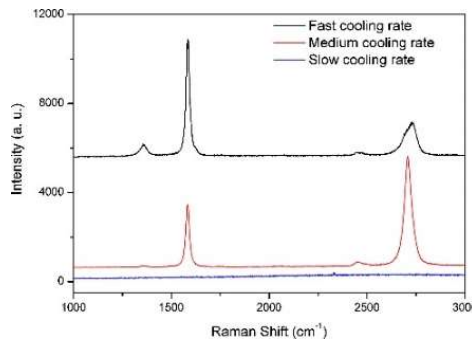
Low carbon solubility



Growth of graphene on Ni

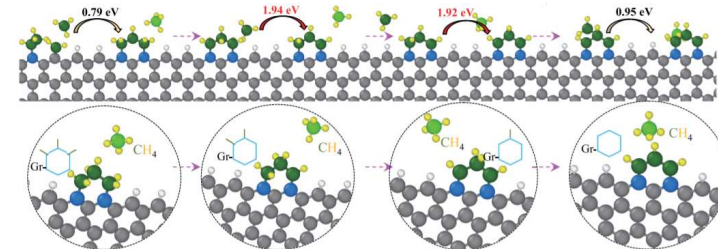


- Cooling rate determines the thickness of graphene.
- Growth of graphene through dissolution and precipitation process of carbon atoms.

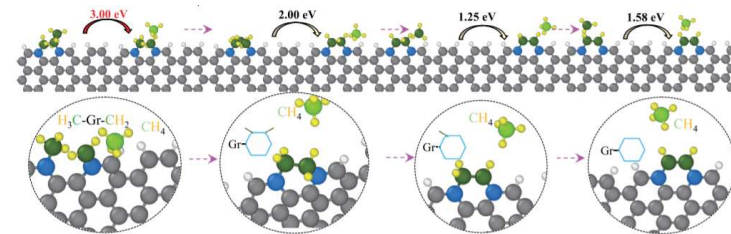


Growth of graphene on insulator

Zigzag edge (ZZ)



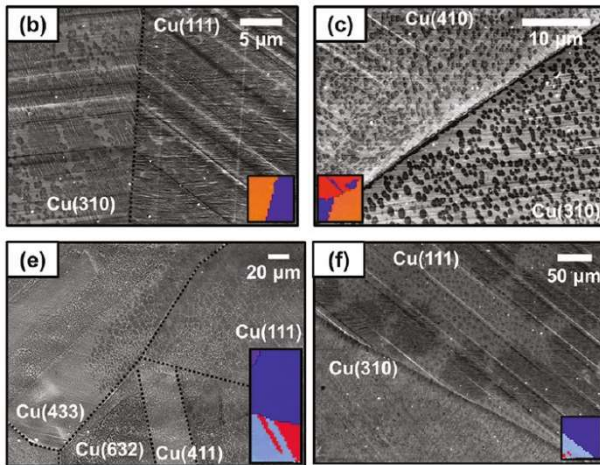
Armchair edge (AC)



- Growth rate of graphene on an insulator is very slow because of high threshold reaction barrier.

Effect of Substrate in CVD

Effect of Copper Surface



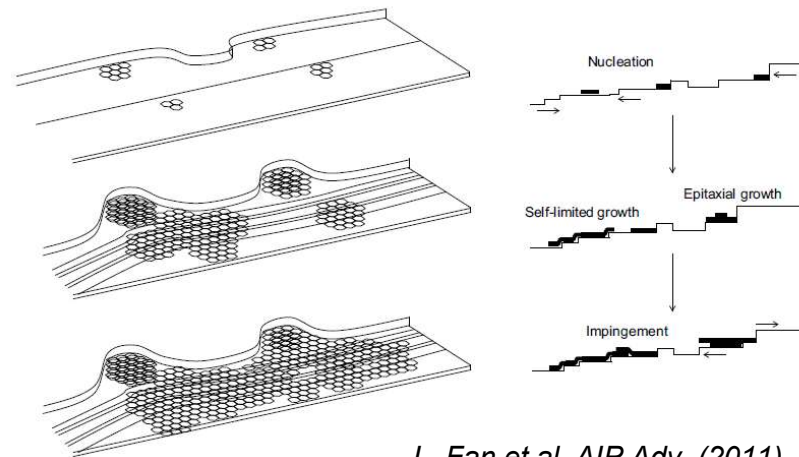
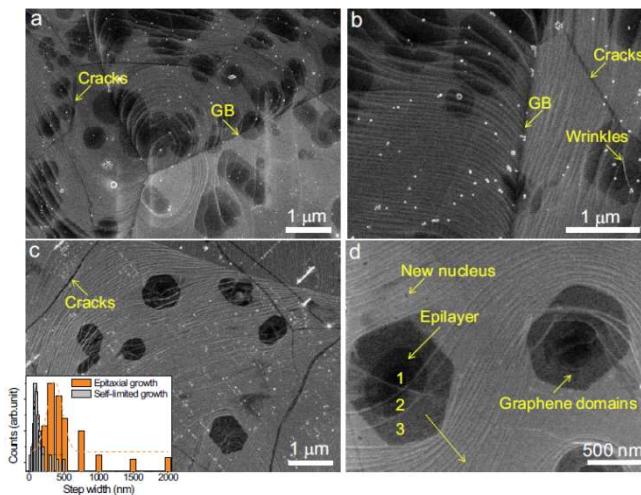
J. Wood et al. Nano Lett (2011)

Low-index Cu facets

More monolayer graphene and fewer defects due to high diffusion and improved adsorption of carbon-containing species on Cu(111)

High-index Cu facets

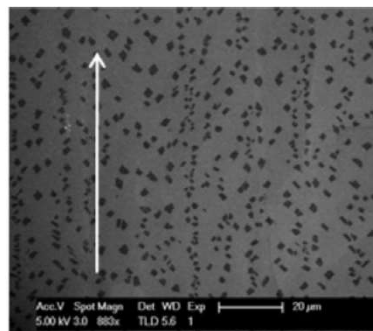
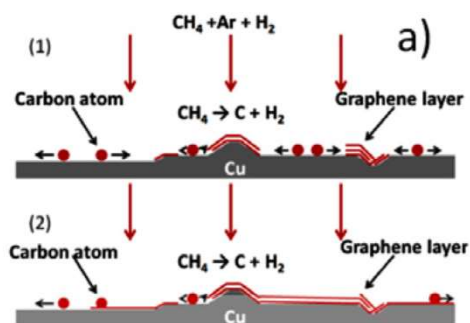
Compact graphene islands due to lowered diffusion, nucleation, and pinning at rough surface sites



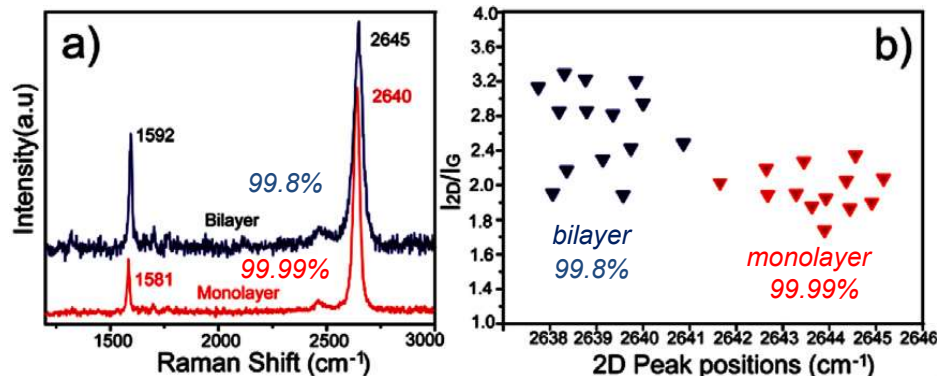
L. Fan et al. AIP Adv. (2011)

Effect of Substrate in CVD

Formation of bilayer patch



Effect of copper purity

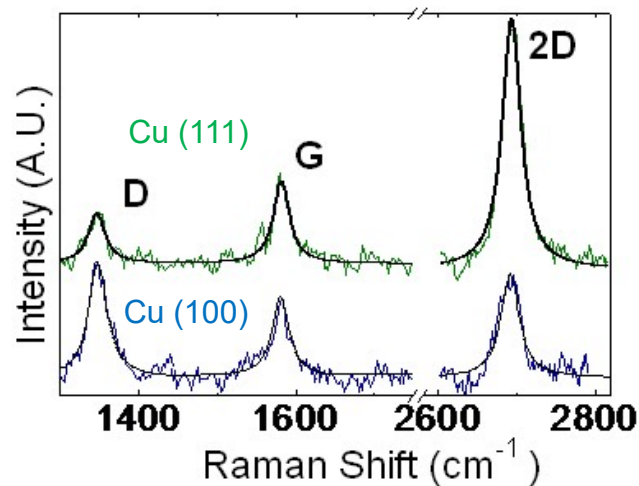
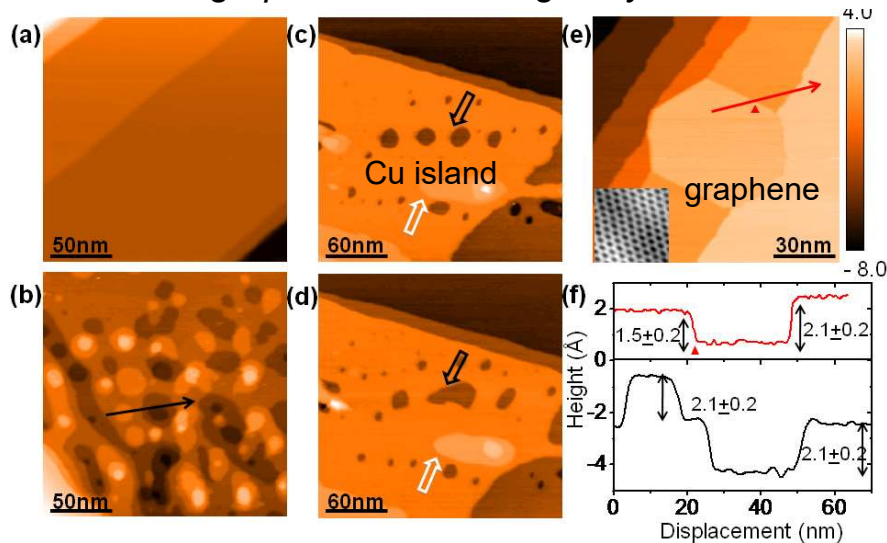


Nucleation of graphene nuclei at steps and grain boundaries.

Diffused impurity atoms onto surface result in growth of bilayer.

W. Liu et al, Carbon (2011)

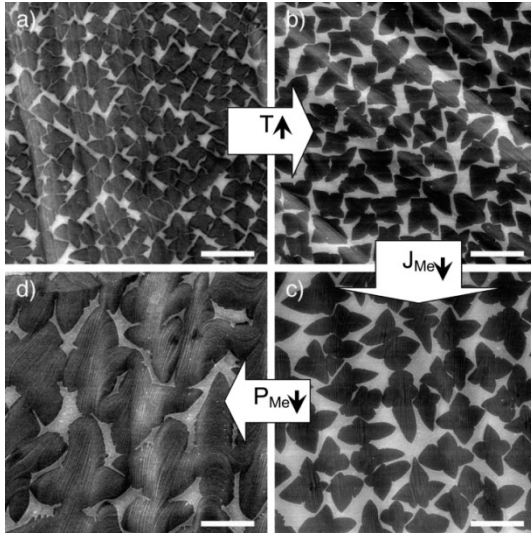
Growth of graphene on Cu single crystal



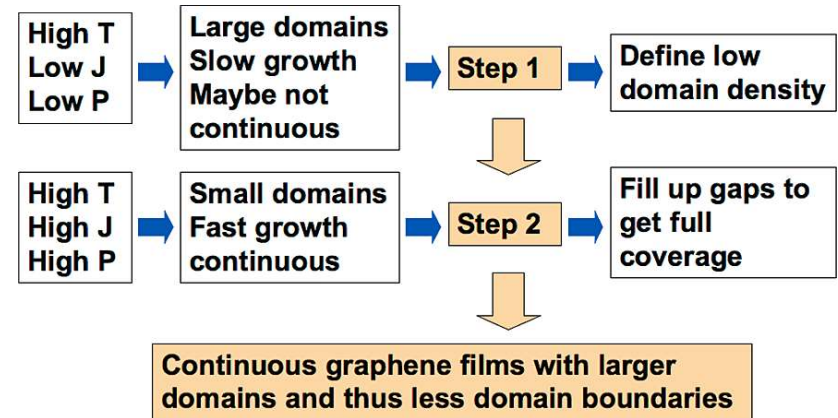
L. Zhao et al. Solid State Communications (2011)

Effect of Growth Conditions in CVD

Effect of Growth Conditions

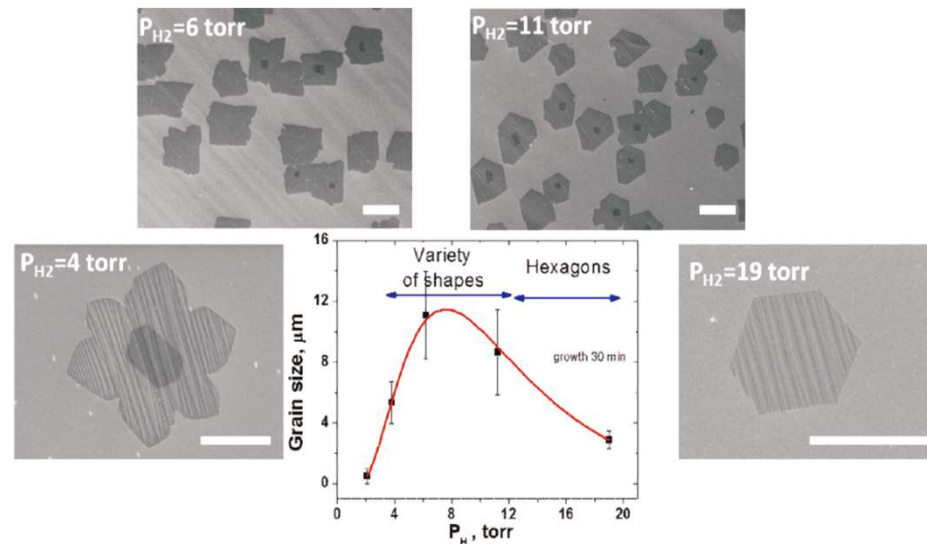


Two-step process for large grain size



X. Li et al. Nano Letter (2010)

Role of Hydrogen in Chemical Vapor Deposition



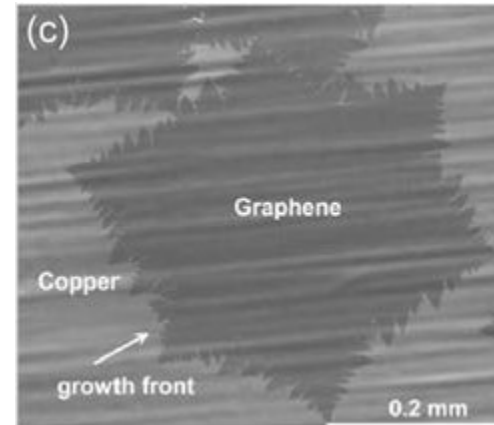
I. Vlassioul et al. ACS Nano (2011)

Effect of Growth Conditions in CVD

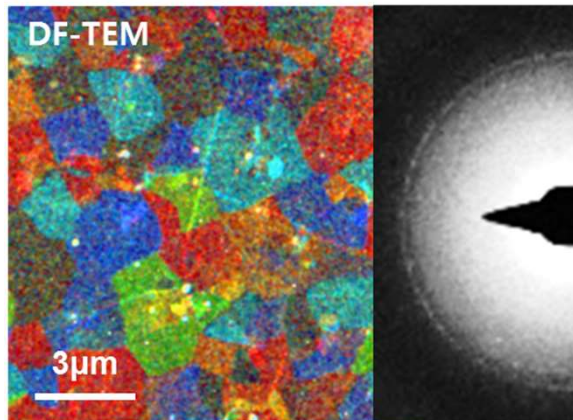
Pita pocket growth



X. Li et al. J. Am. Chem. Soc. (2011)

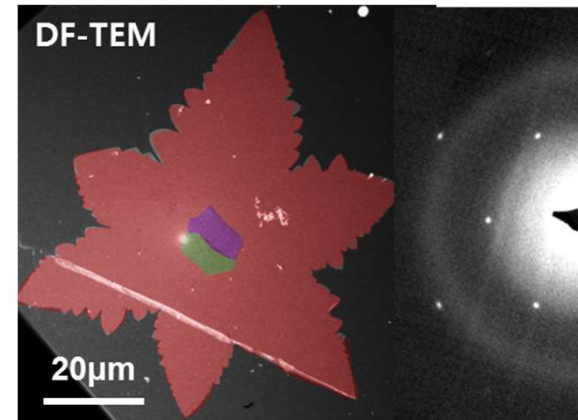


Small Grain Graphene



- Pressure: 300 mTorr
- Flow rate: 35 sccm methane
- Directly exposed on copper foil
- multi-grain graphene with 1-5 μm size

Large Grain Graphene

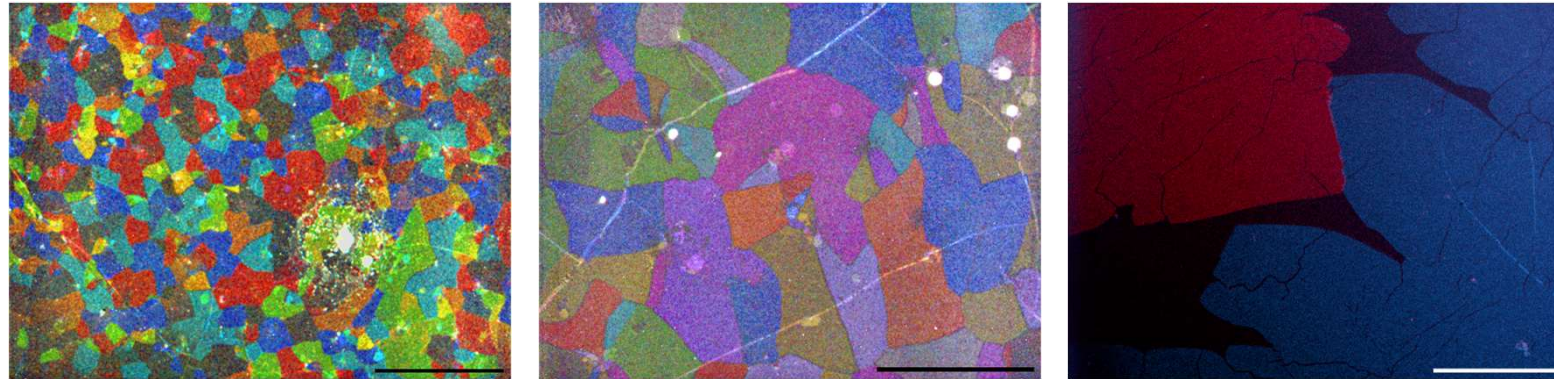


- Pressure: <50 mTorr
- Flow rate: 1 sccm Methane
- Enclosed copper foil (by Ruoff group)
- single-grain graphene with 100-150 μm

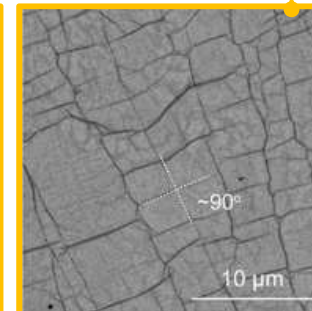
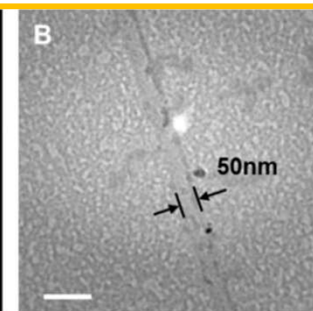
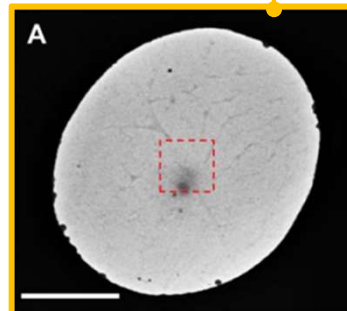
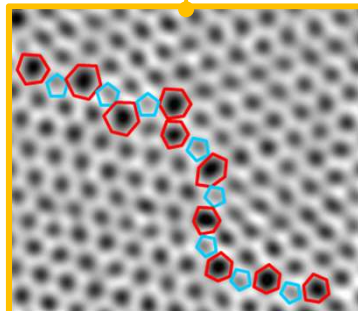
G. H. Lee et al. Science (2013)

Types of Grain Boundaries in CVD-grown Graphene

Larger grain size (lower flow of CH₄) →

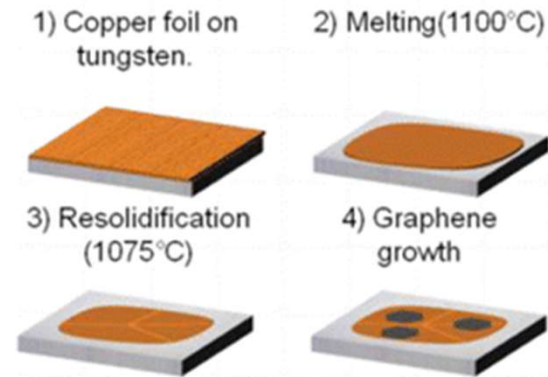
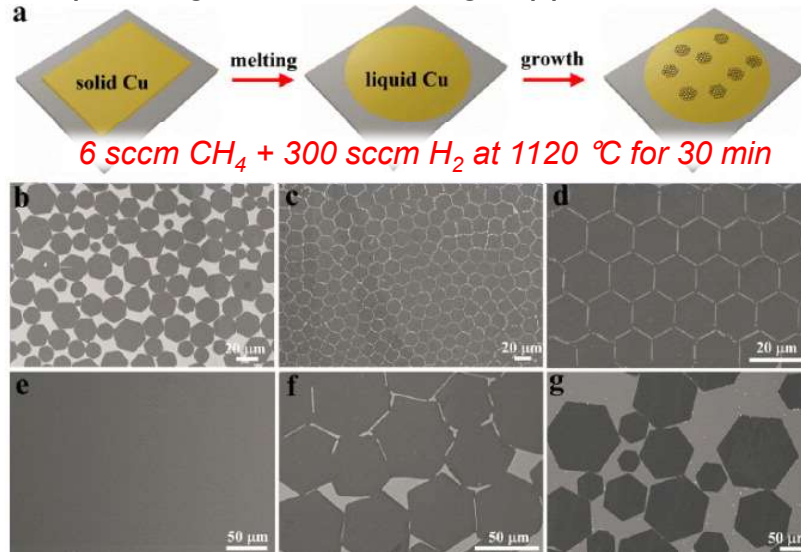


	Stitched GB	Overlapped GB	Standing Collapsed Wrinkle	Folded Wrinkle
Shape				
Width	3 ~ 4 Å	10 ~ 50 nm	~ 2 nm (first observed)	~ 100 nm
Height			2 ~ 6 nm	~ 1 nm



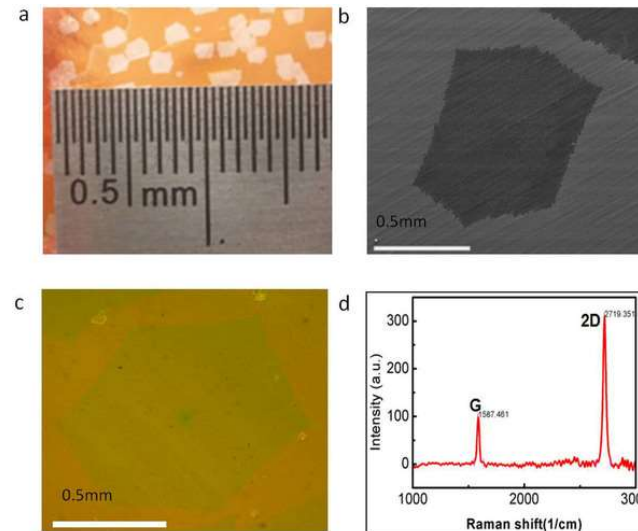
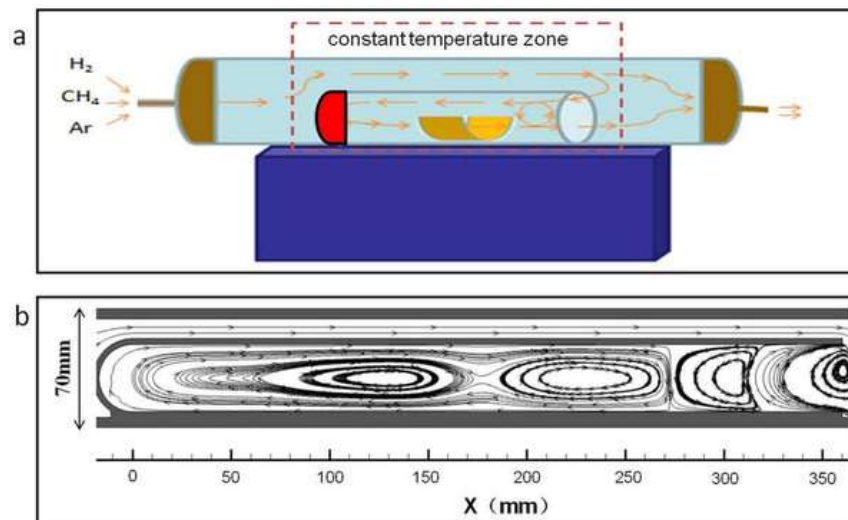
Effect of Growth Conditions in CVD

Graphene growth on melting copper



D. Genget al. PNAS (2012) & A. Mohsin et al. ACS Nano (2013)

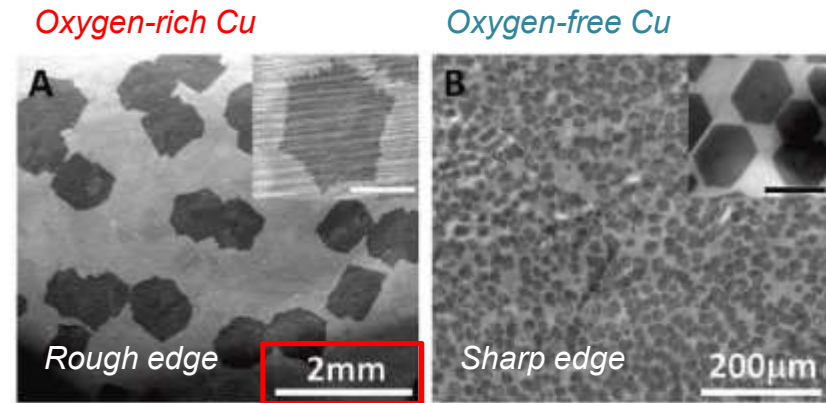
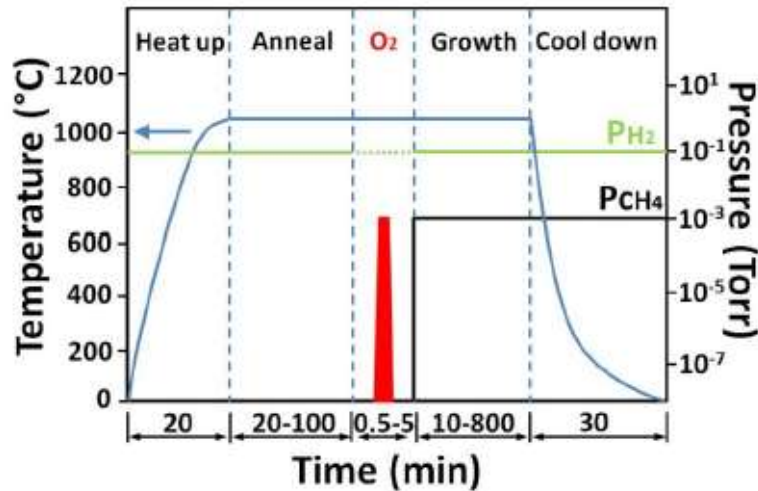
Circumfluence CVD



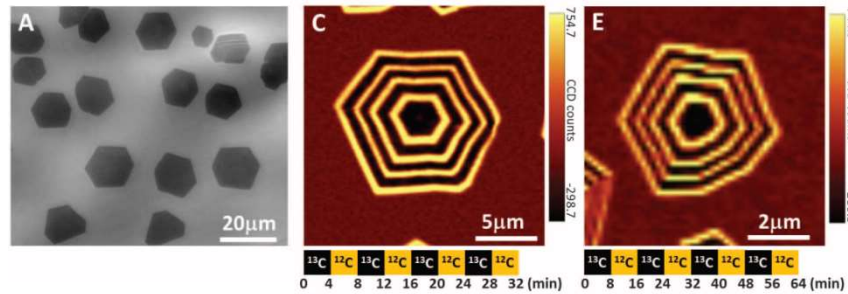
C. Wang et al. Sci. Rep. (2014)

Effect of Growth Conditions in CVD

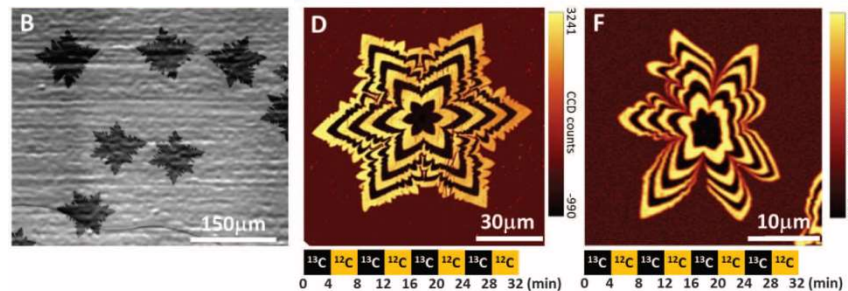
Suppression of graphene nucleation by oxygen on the copper surface



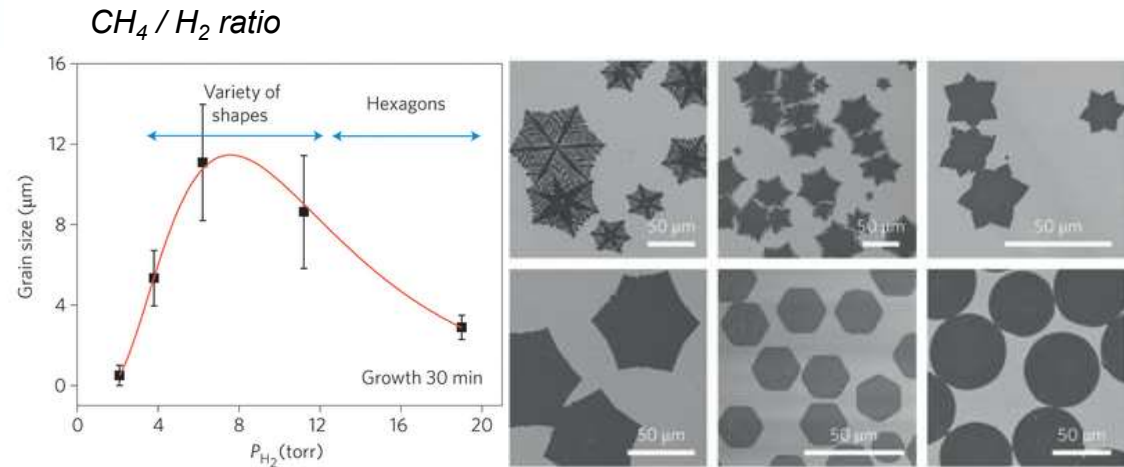
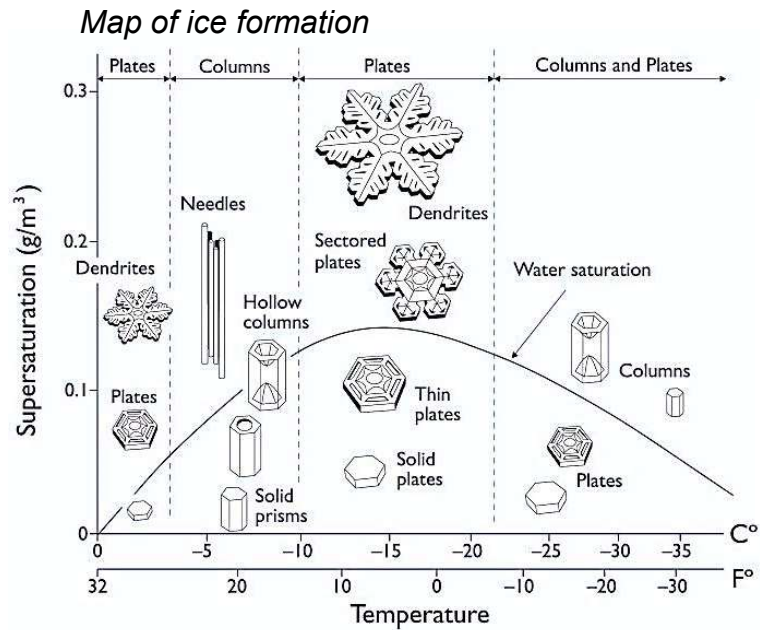
Oxygen-rich Cu



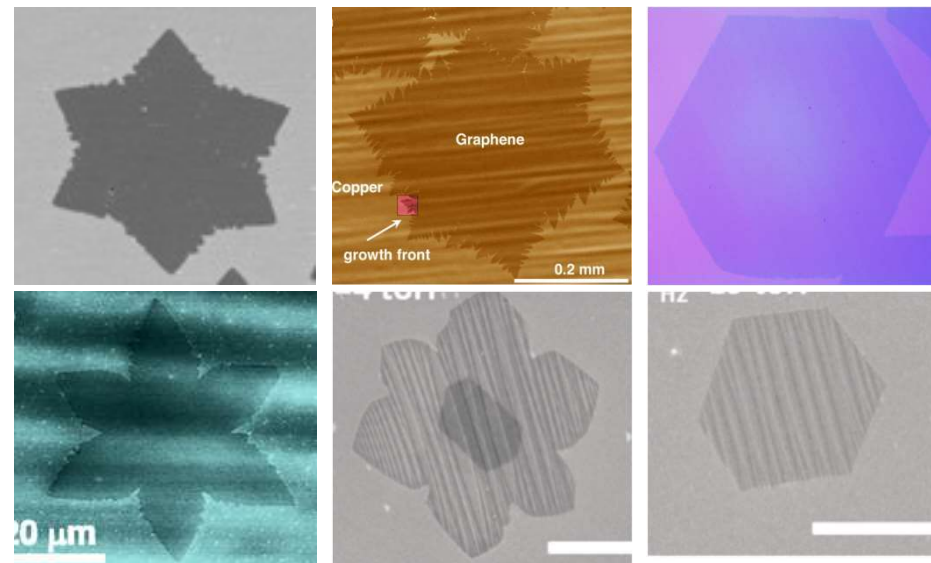
Oxygen-free Cu



Shape Control of CVD-Grown Graphene

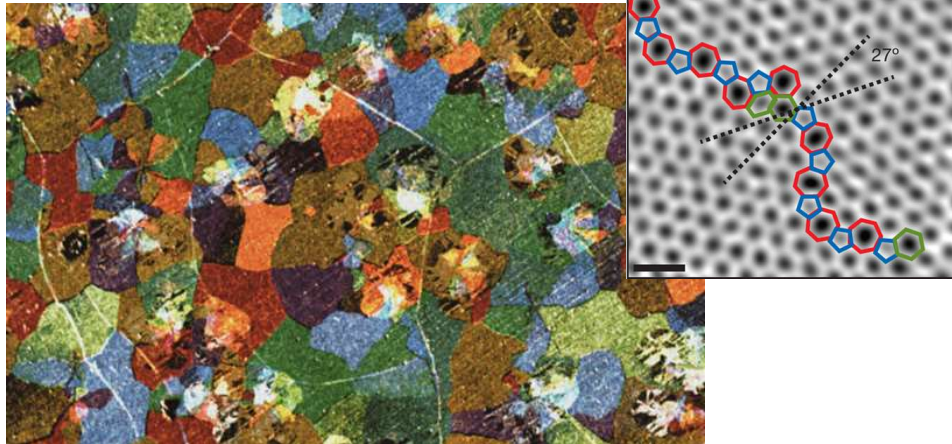


O. V. Yazyev et al. *Nature Nanotechnol.* (2014)



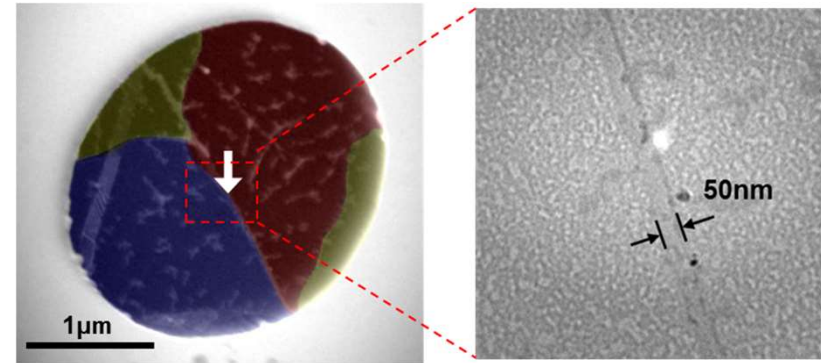
Grain Boundaries of CVD-Grown Graphene

Graphene patchwork quilt



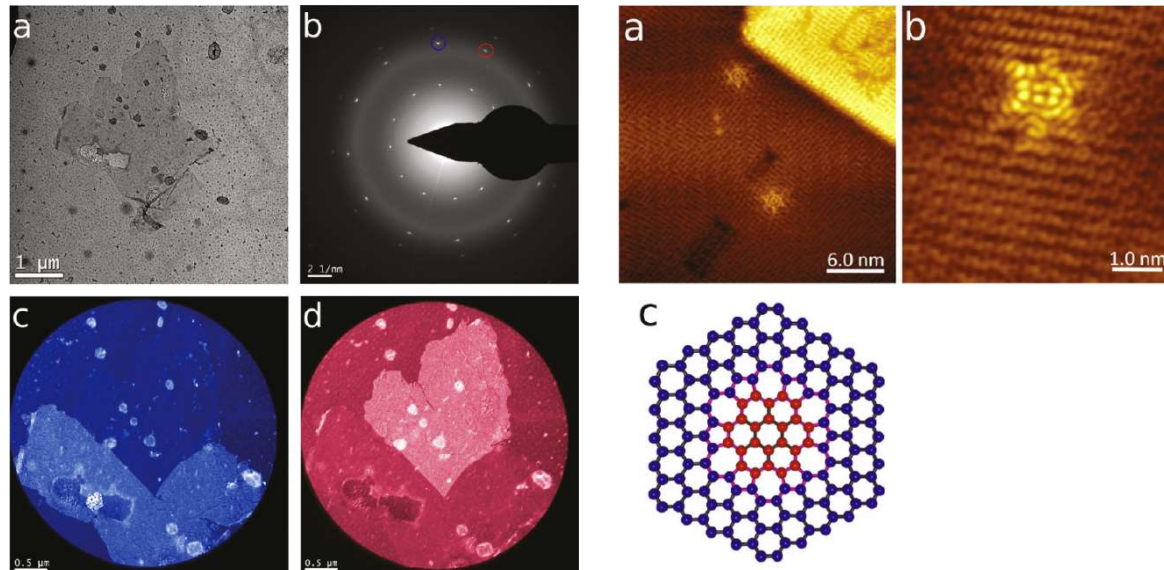
P. Huang et al. Nature (2011)

Overlapped Grain Boundaries (Un-stitched)



G. H. Lee et al. Science (2013)

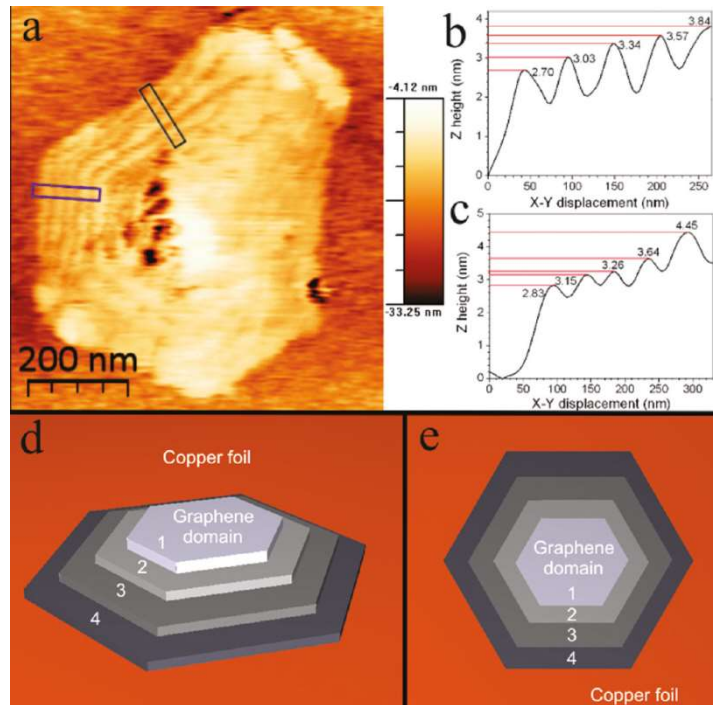
Graphene grown Cu (100) single crystal



H. Rasool et al. JACS (2011)

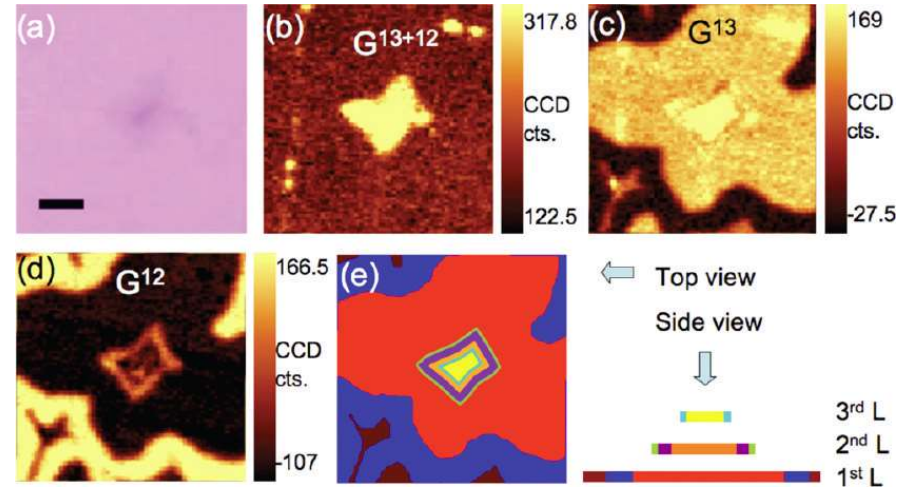
"flower" structures at small protrusions

Growth of Multilayer Graphene Islands



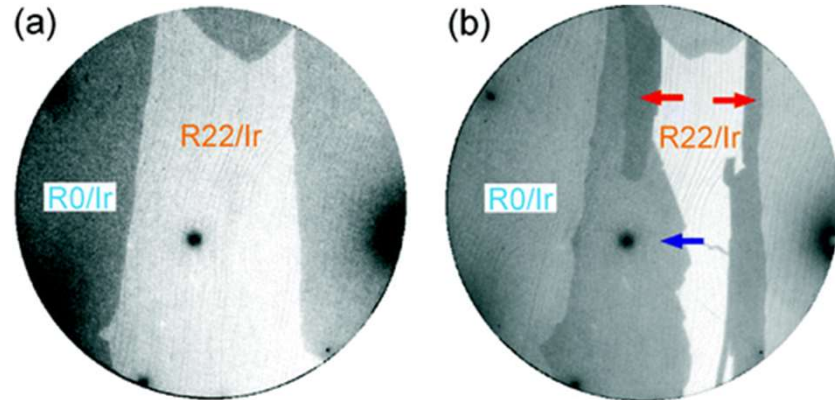
A. W. Robertson et al. *Nano Lett.* (2011)

Raman mapping using carbon isotopes

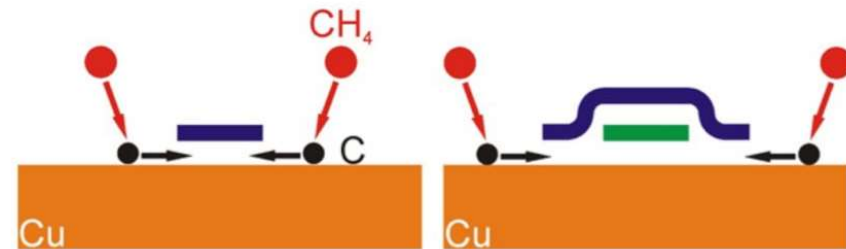


X. Li et al. *Nano Lett.* (2009)

Growth from below: graphene bilayers



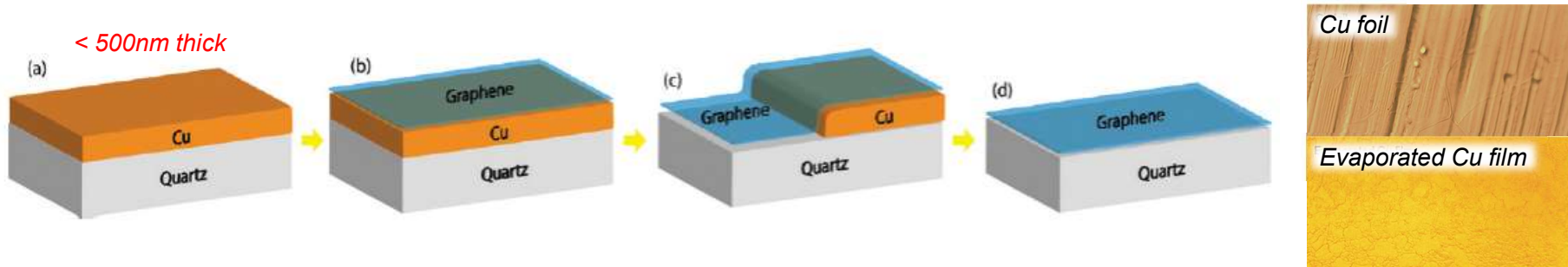
CVD



S. Nie et al. *ACS Nano* (2011)

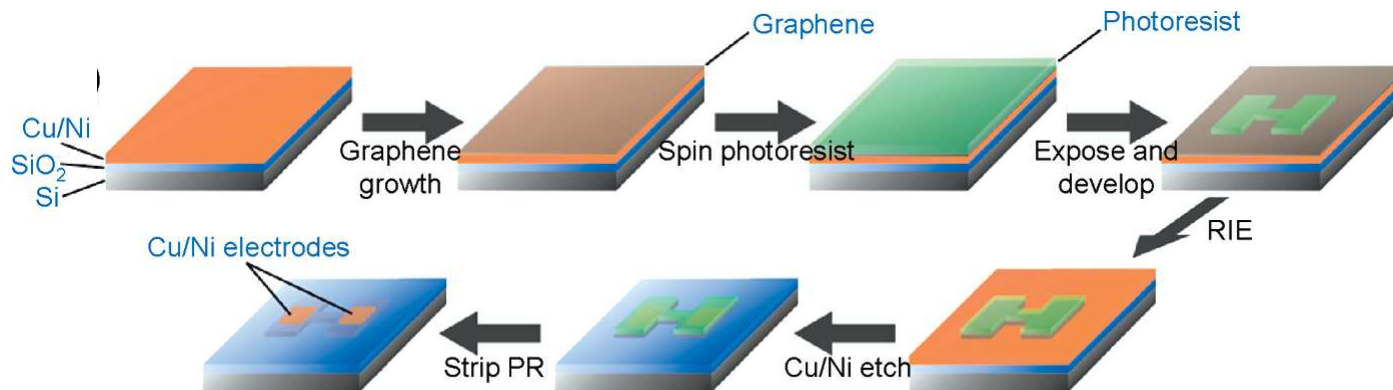
Advances in CVD Process for Graphene

Direct transfer of CVD-grown graphene onto SiO_2 substrate



A. Ismach et al. Nano Lett. (2010)

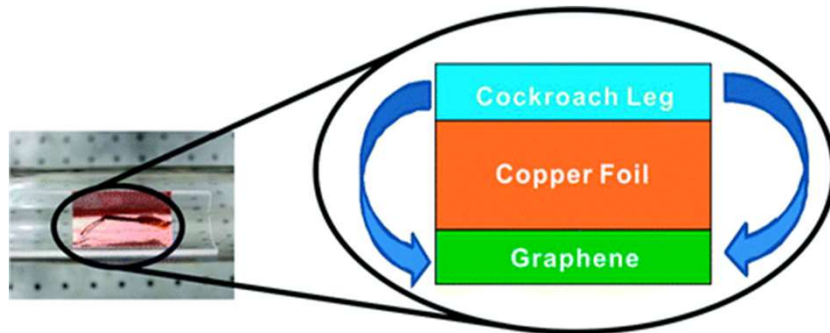
Direct fabrication of electrode in CVD-grown graphene devices



M. P. Levendorf et al. Nano Lett. (2009)

Advances in CVD Process for Graphene

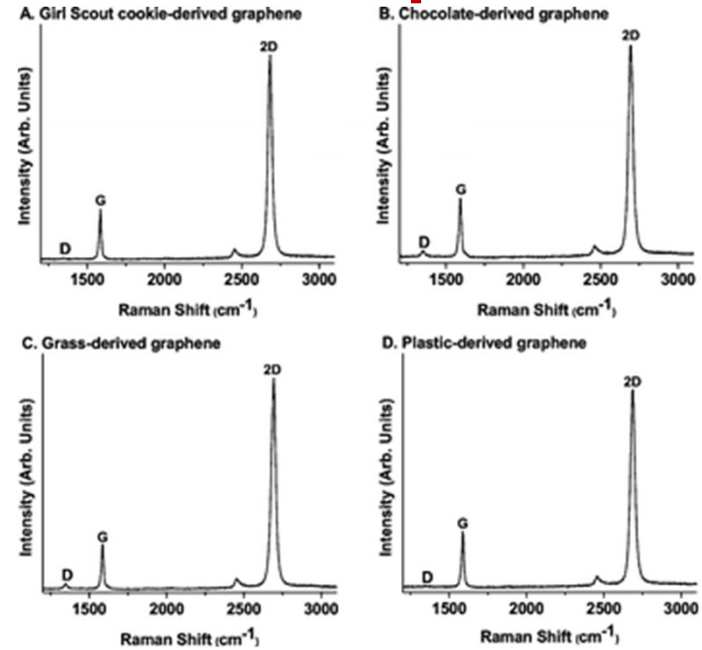
Growth of Graphene from Food, Insects, and Waste



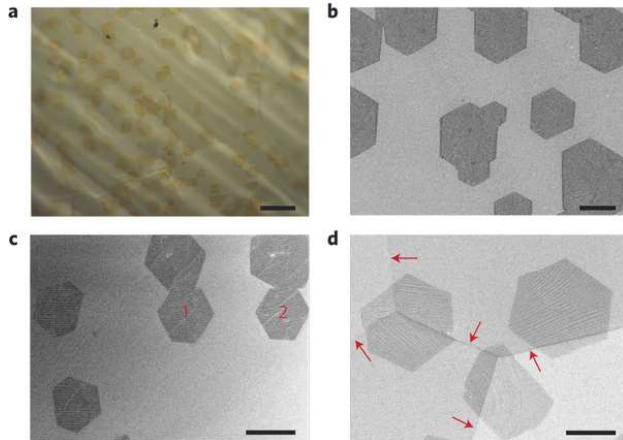
Cockroach leg before conversion to graphene

Cross view of the growth of graphene on the backside of the Cu foil

G. Ruan et al. ACS Nano (2011)

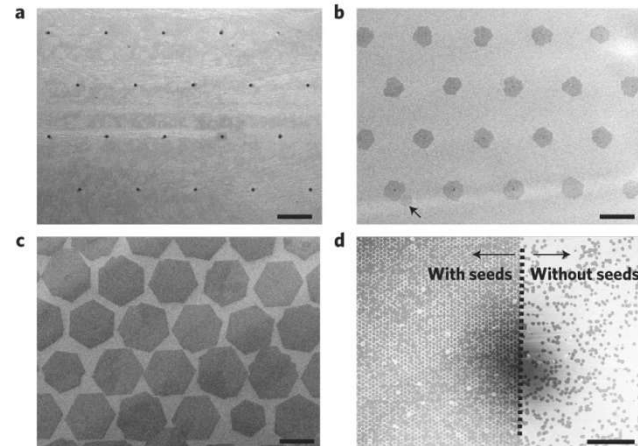


Aligned growth of large-size graphene grains



Growth at 1050 °C for ~10 min under 300 sccm diluted CH₄ (8 ppm in Ar) and 10 sccm of H₂

Seeded growth of graphene

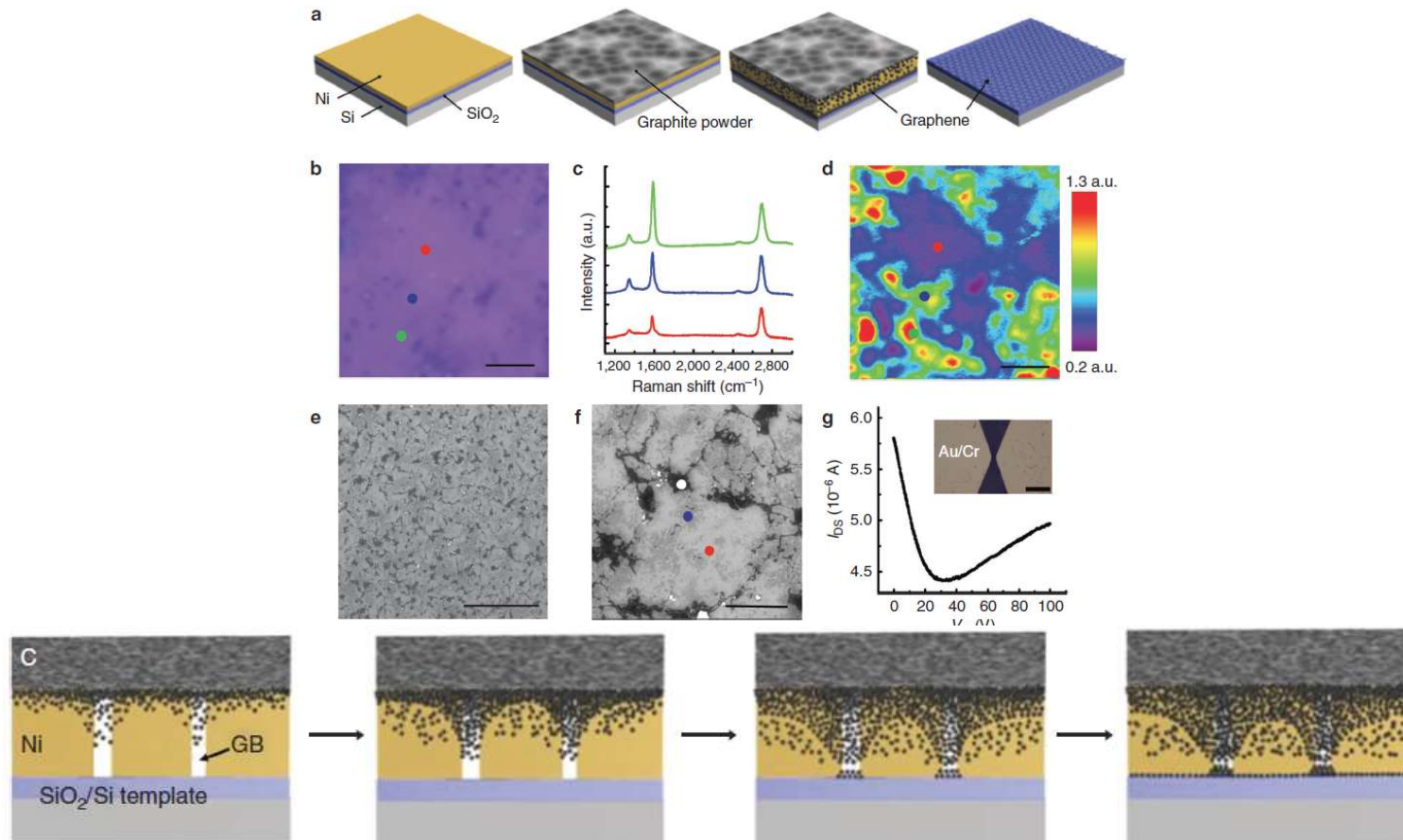


Seeds of patterned graphene for control of nucleation sites

Q. Yu et al., Nature Materials (2011)

Advances in CVD Process for Graphene

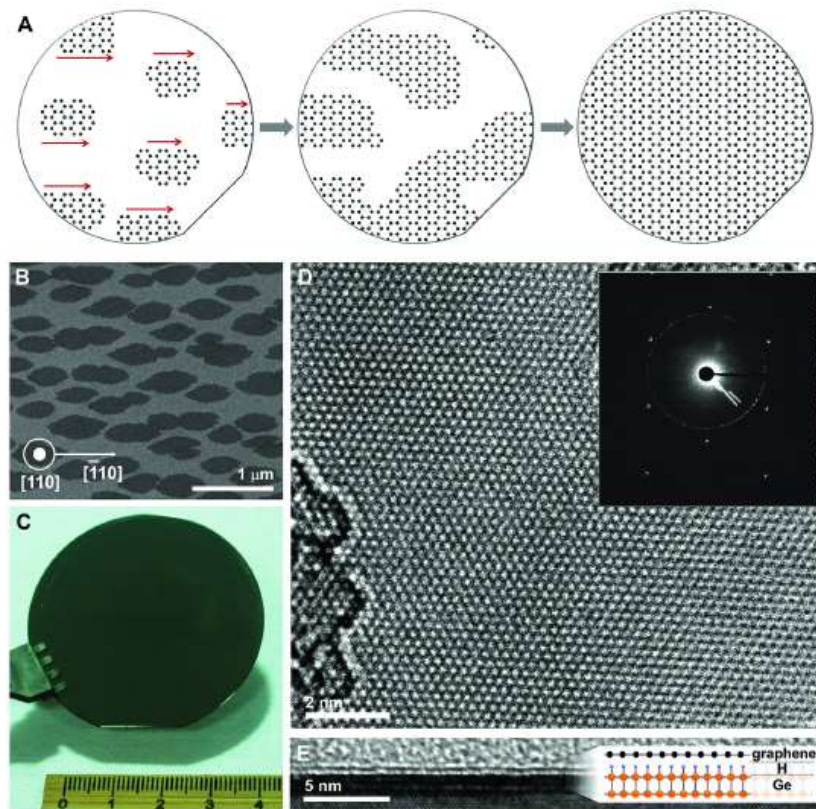
Near room-temperature synthesis of transfer-free graphene films



J. Kwak et al. Nature Commun. (2012)

Advances in CVD Process for Graphene

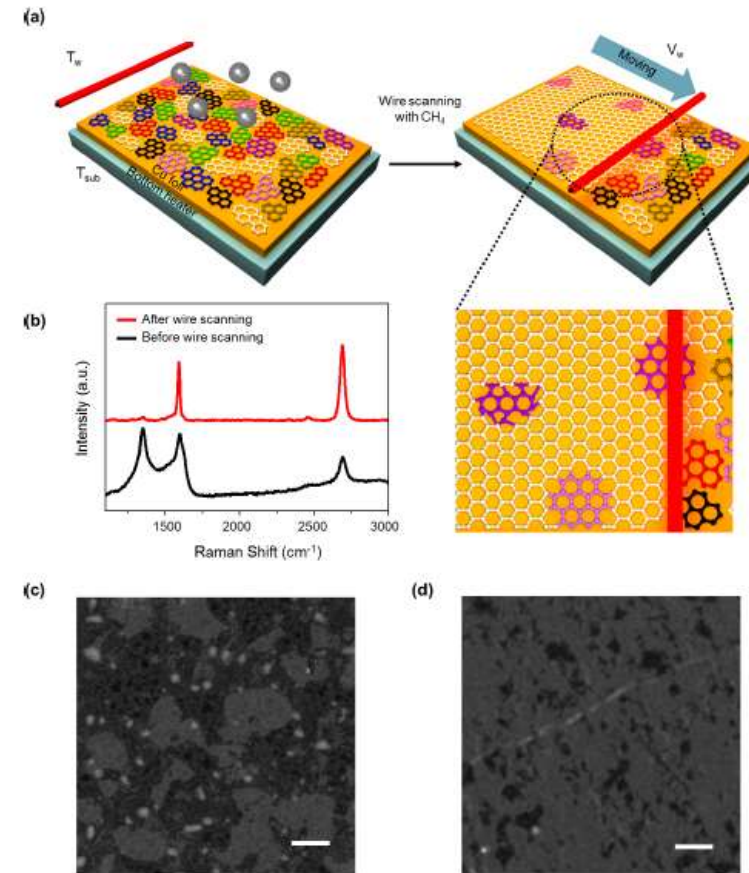
Large-Single-Crystal Graphene



Growth of graphene on H_2 terminated Ge surface

J. H. Lee et al. Science (2014)

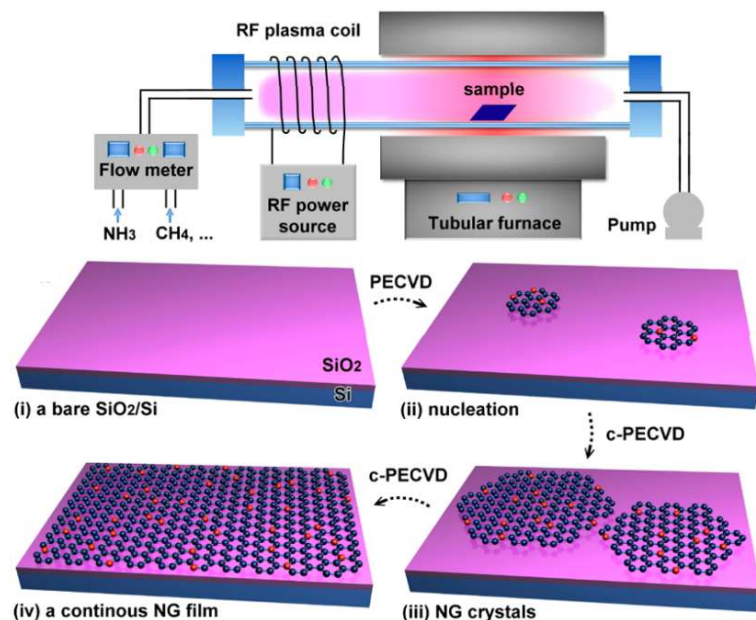
Removal of Grain Boundaries



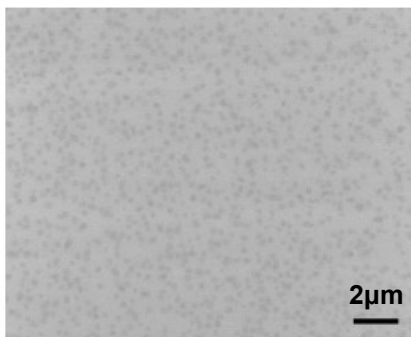
J. Lee et al. Nano Lett. (2014)

Advances in CVD Process for Graphene

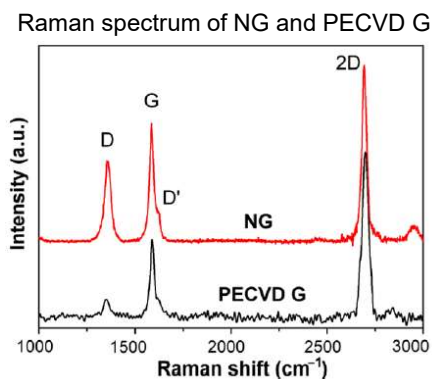
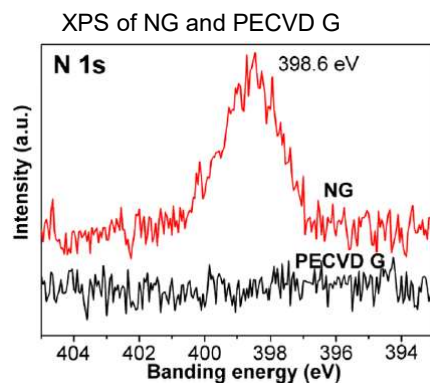
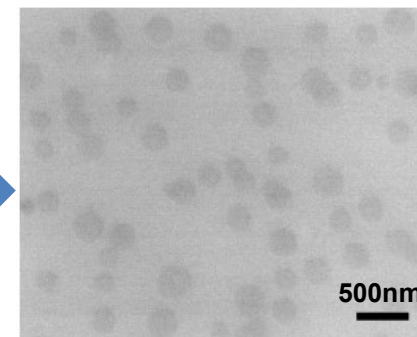
N-doped graphene growth on SiO₂ using PECVD under 700 °C



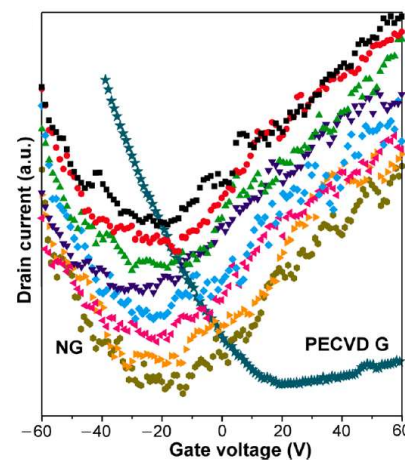
Seed nucleation at 700°C



Growth at 650°C



Transfer curve of NG and PECVD G



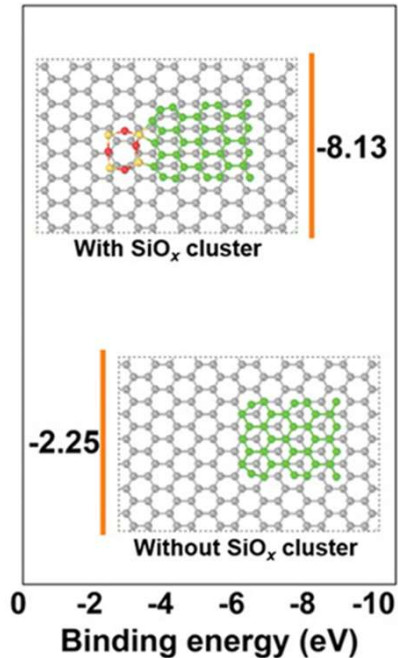
NG – nitrogen doped graphene made by CH₄ + NH₃ in PECVD

PECVD G – pristine graphene made by CH₄ + H₂ in PECVD

Advances in CVD Process for Graphene

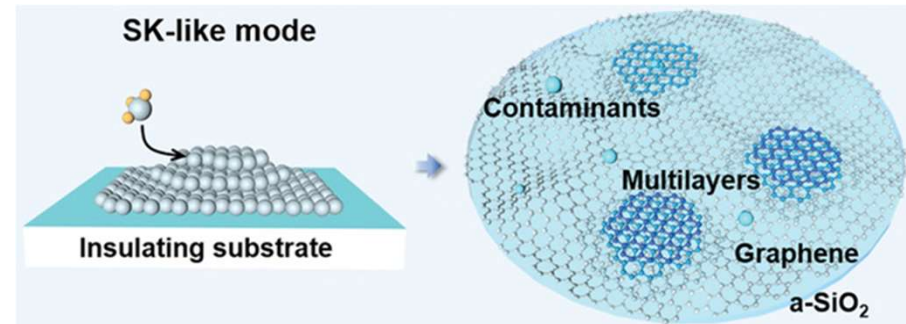
Graphene nucleation and growth behaviors over amorphous SiO_2 substrate

Binding energy of graphene

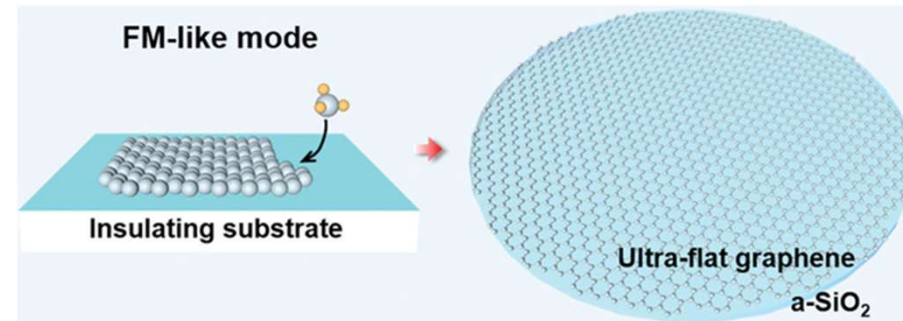


Binding energy of underlayer and overlayer with the presence of Si_4O_4 cluster is -8.13 eV, much higher than that of bare graphene (-2.25 eV), indicating that unsaturated carbon atoms of nanofragments are prone to deposit on the surface of graphene aided by Si_4O_4 cluster.

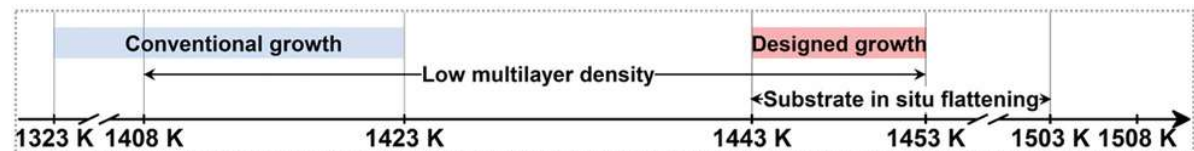
Conventional CVD



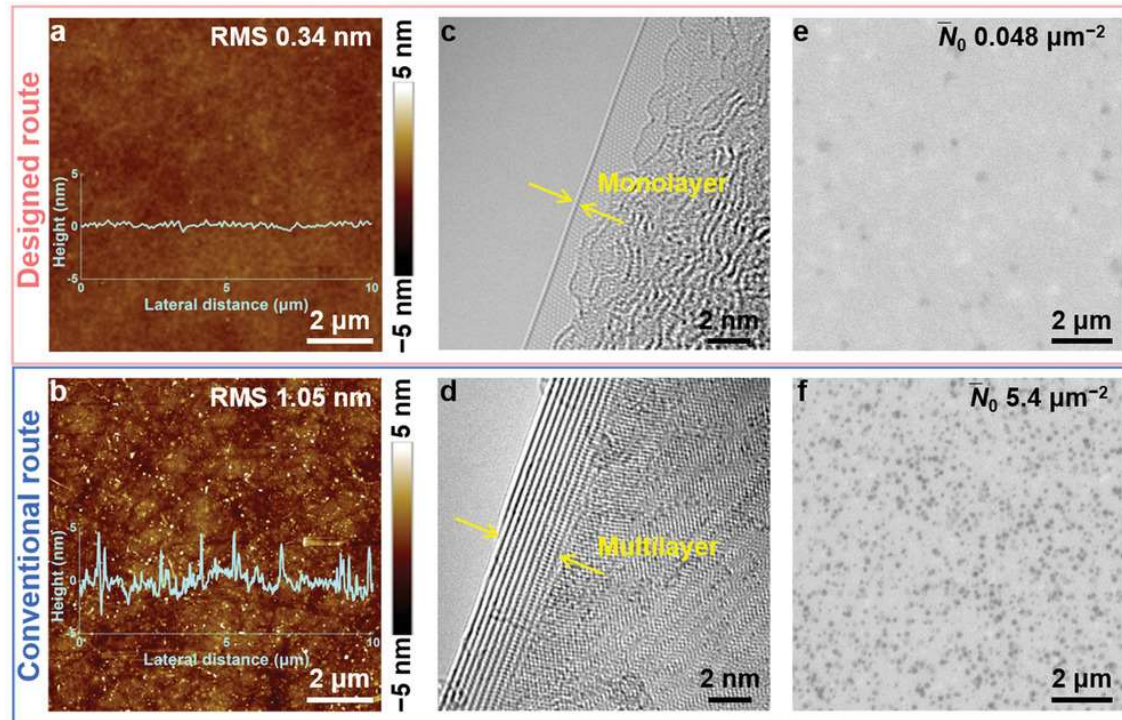
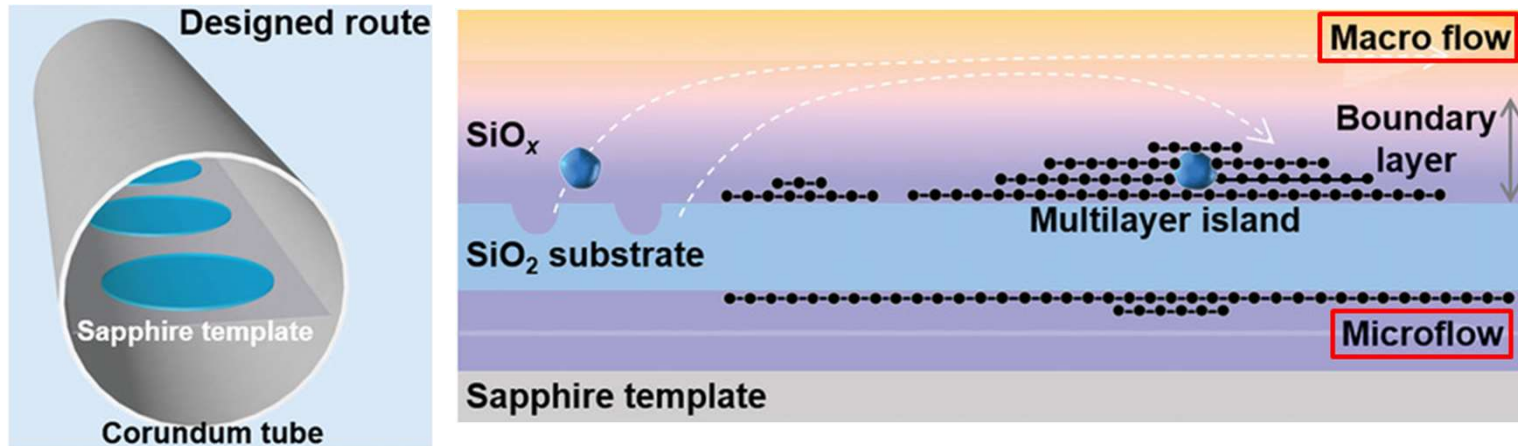
Designed CVD



Temperature ranges for designed and conventional CVD

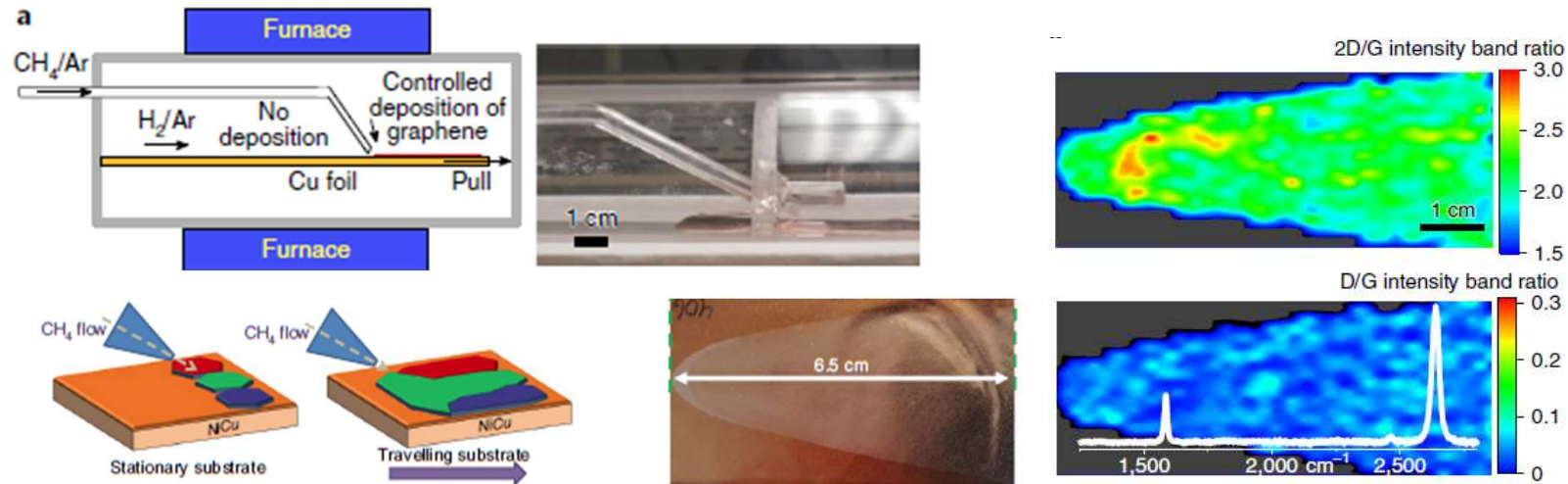


Advances in CVD Process for Graphene



Advances in CVD Process for Graphene

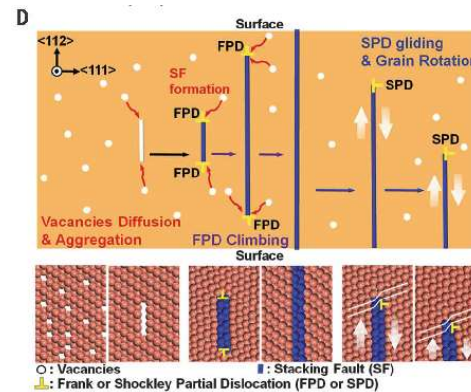
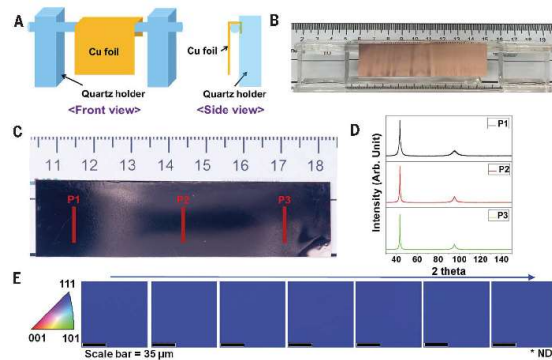
Advancing Local Control CVD (ALC CVD)



I. Vlasiouk et al. Nature Materials (2018)

Growth of graphene on Cu (111) single crystal

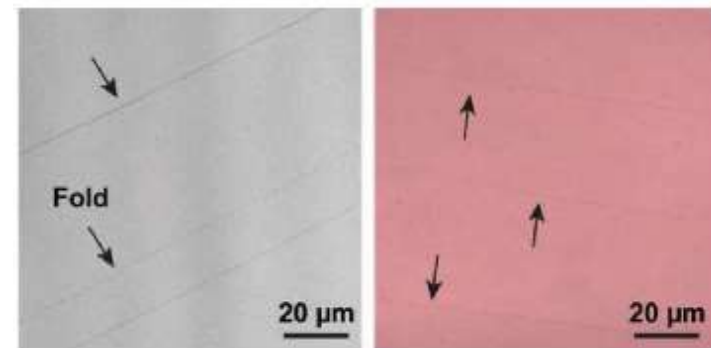
Contact free annealing (CFA) of Cu



S. Jung et al. Science (2019)

SEM image of graphene on a Cu (111) foil

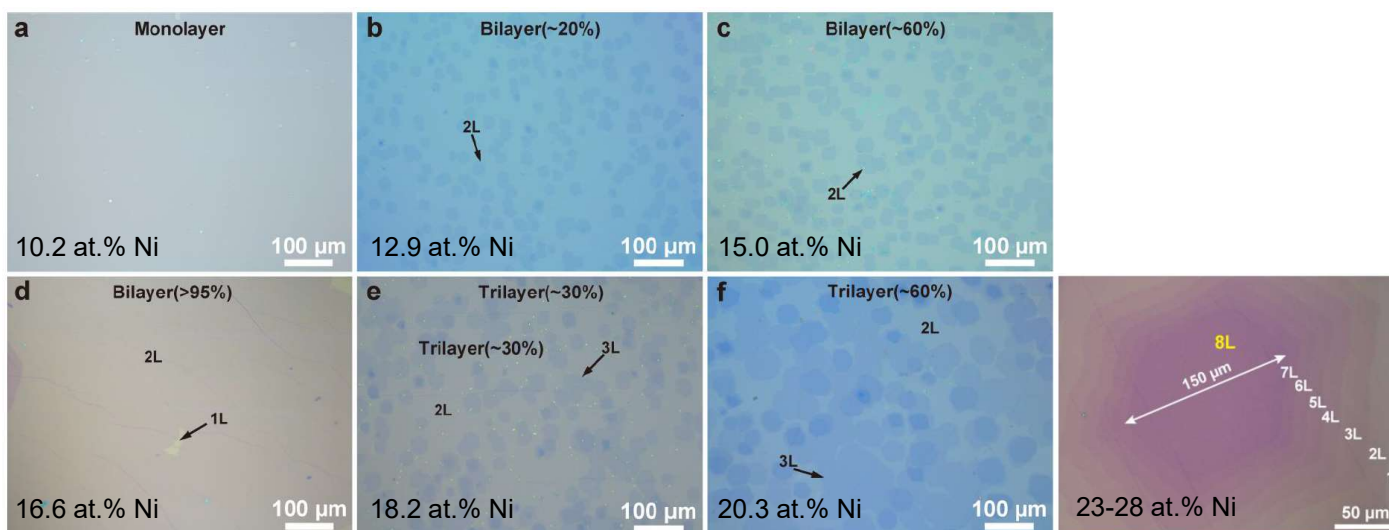
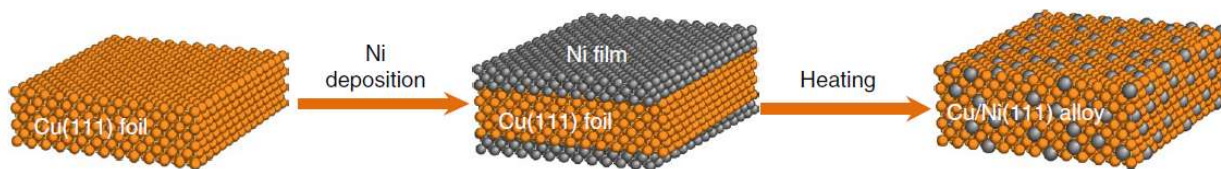
OM image of and graphene transfer to a 300 nm SiO_2/Si



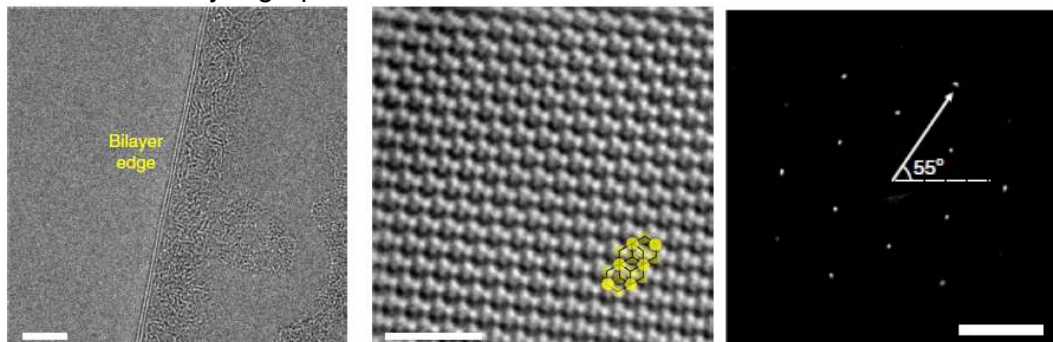
D. Luo et al. Adv. Mater. (2019)

Advances in CVD Process for Graphene

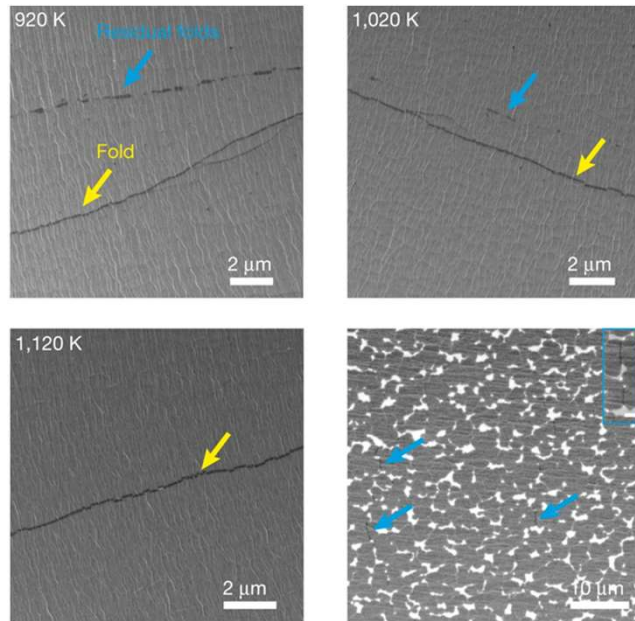
Layer control of graphene using Cu/Ni(111) alloy



AB stacked bilayer graphene

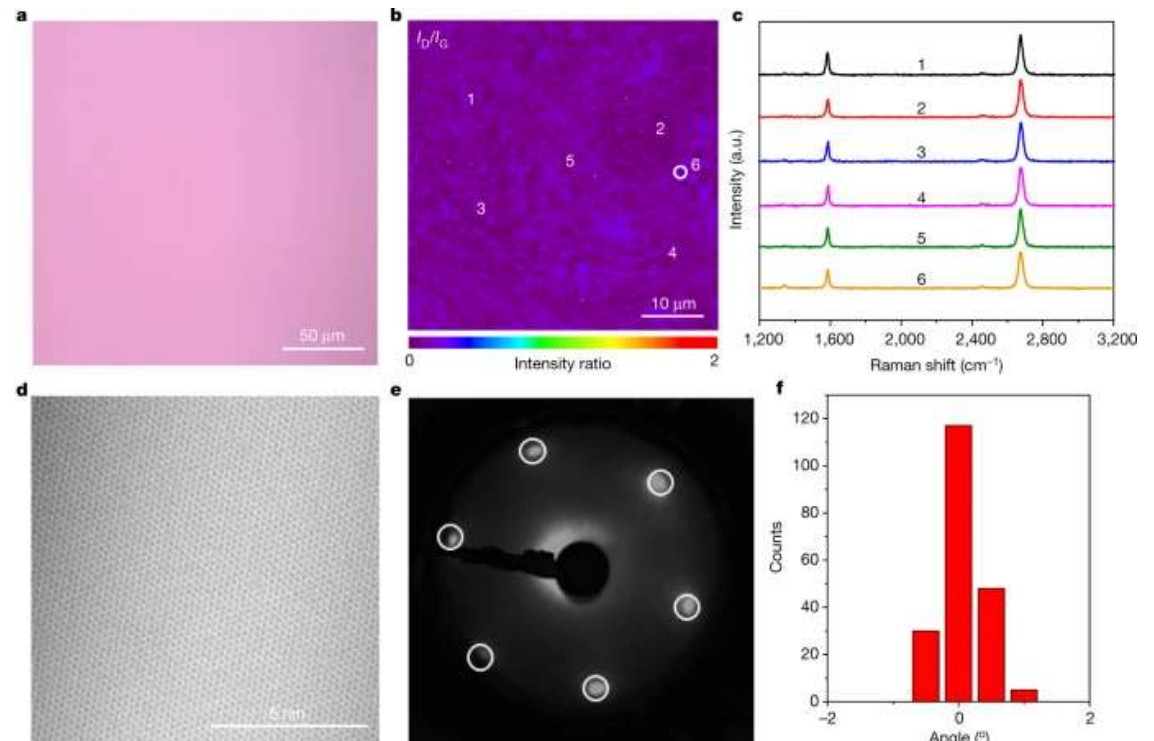
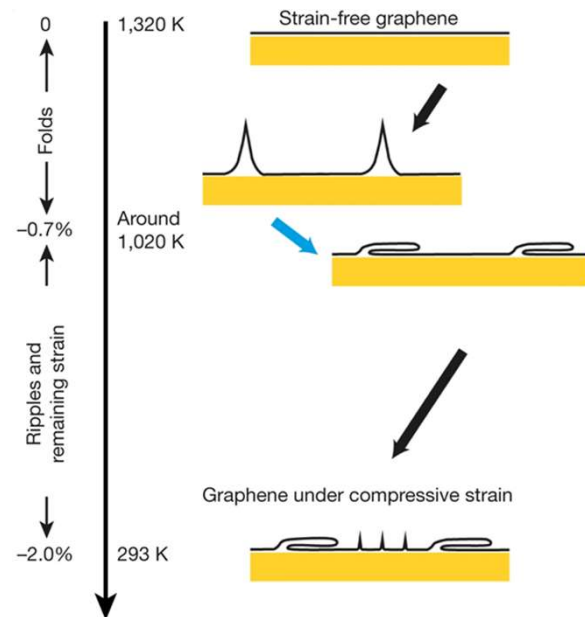


Advances in CVD Process for Graphene



Cycling experiment: Growth at 1320K, then cooling to different temperatures (920K, 1,020K, 1120K) and stabilizing for 10 min, followed by regrowth at 1,320 K for 30 min

Single-crystal, large-area, fold-free monolayer graphene
 : Critical temperature for the formation of folds is 1030K on Cu–Ni(111) alloy foil with ethylene (carbon precursor)



Observation of Grain Boundaries in Graphene

